



# MEBT Laser Notcher (Chopper) for Booster Loss Reduction

D.E. Johnson, T. R. Johnson, C. Bhat, S. Chaurize , K. Duel, P. Karns, W. Pellico, B. Schupbach,  
K. Seiya, D. Slimmer

ICFA Workshop on High Brightness Beams – HB2018  
Daejeon, South Korea  
21-June-2018

# Acknowledgements

---

- Bob Zwaska
- Fernanda Garcia
- Bill Pellico
- Matt Gardner
- Chandra Bhat
- Pat Karns
- Brian Schupbach
- Dan Bollinger
- Drew Feld
- Ben Ogert
- Jason Kubinski
- Justin Briney
- Jeff Larson
- Fred Mach
- Katrina Hunden
- Mike Kucera
- Bobby Santucci
- Tom Boes
- Jinhao Ruan
- Jamie Santucci
- Andrea Saewert
- Vic Scarpine
- Randy Keup
- Alex Lumpkin
- Matt Quinn & Dave Baird (LSO)
- ES&H Interlock Group
- Alignment crew
- KV Reddy & Sreenivas Patel of [PriTel](#)
- Don Sipes & Jason Tafoya of [Optical Engines](#)
- Jay Doster & Dennis Lockwood [Grumman](#)
- Plus many others



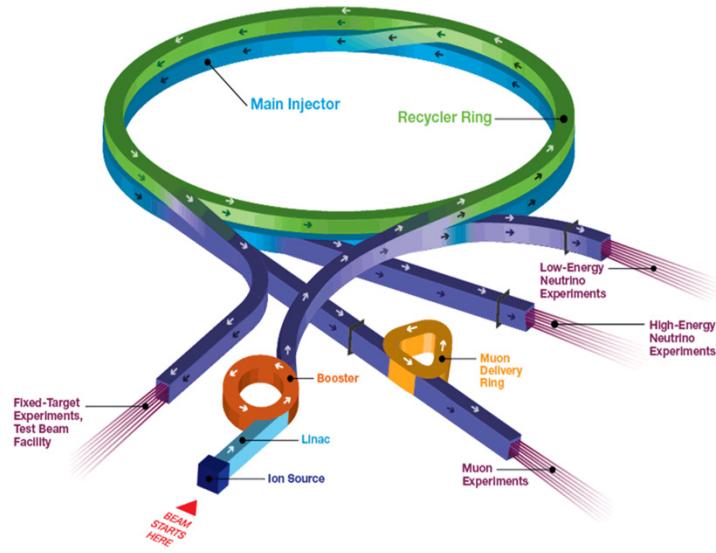
## Outline

---

- Introduction to Fermilab
- Introduction to Proton Source
- Laser Notcher System
- Booster Injection with Notches in Linac beam
- Operational Impact
- The un-expected
- Path forward
- Summary

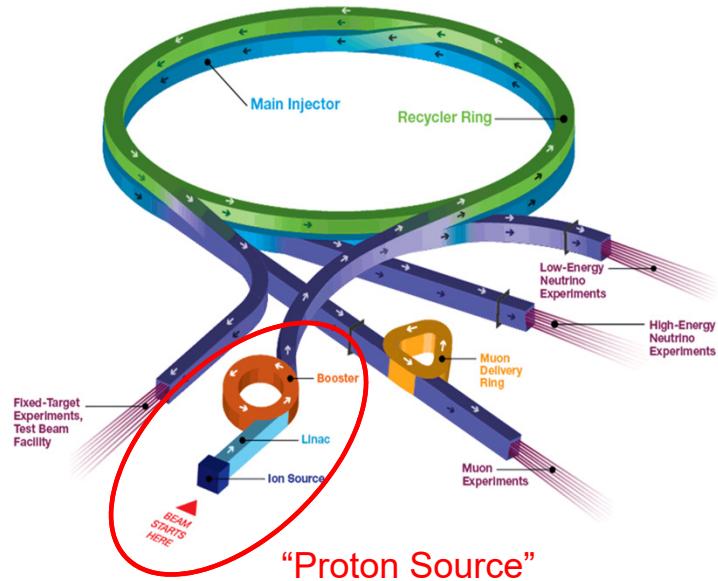
# Introduction to Fermilab Accelerators & a Little History

Fermilab Accelerator Complex



# Introduction to Fermilab Accelerators & a Little History

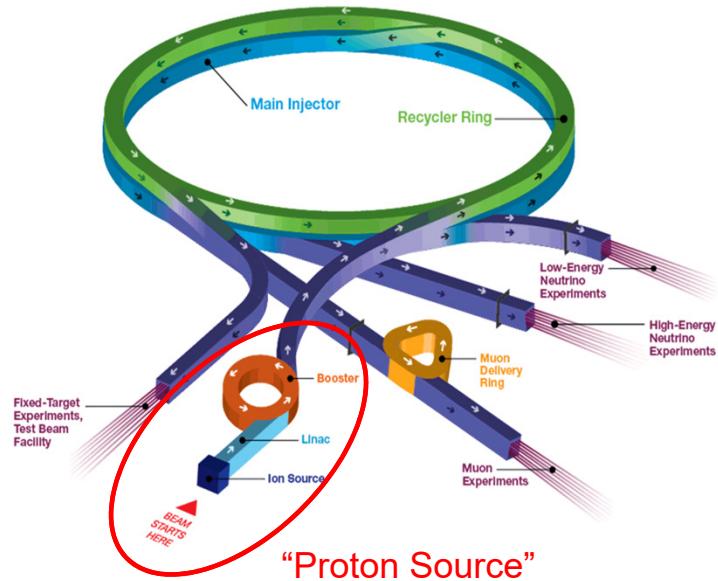
Fermilab Accelerator Complex



# Introduction to Fermilab Accelerators & a Little History

Transitioning from Energy to Intensity Frontier

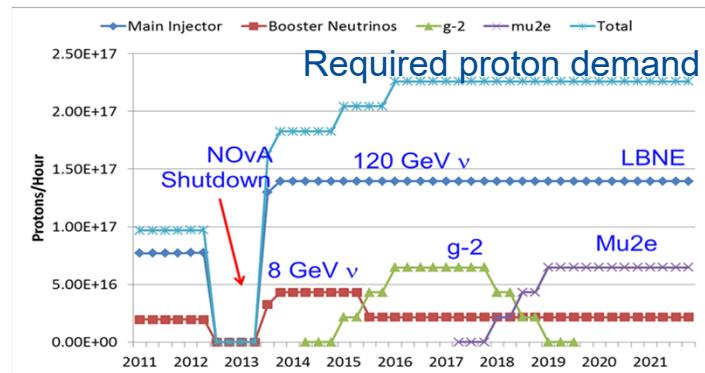
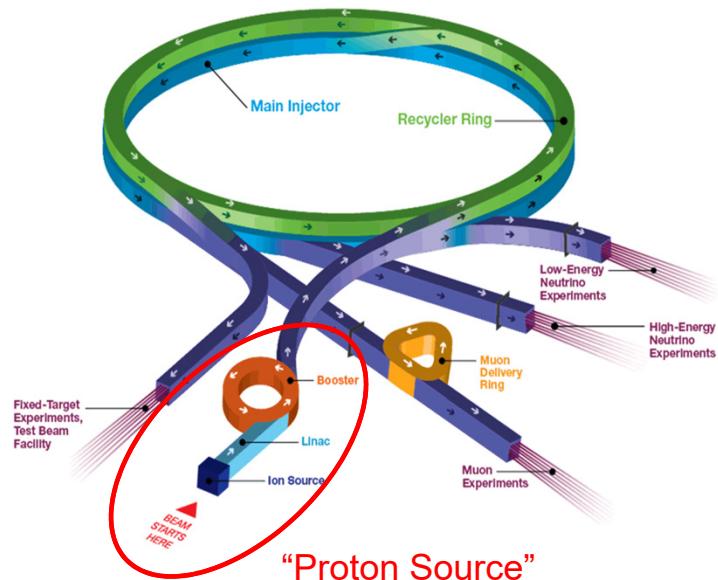
Fermilab Accelerator Complex



# Introduction to Fermilab Accelerators & a Little History

Transitioning from Energy to Intensity Frontier

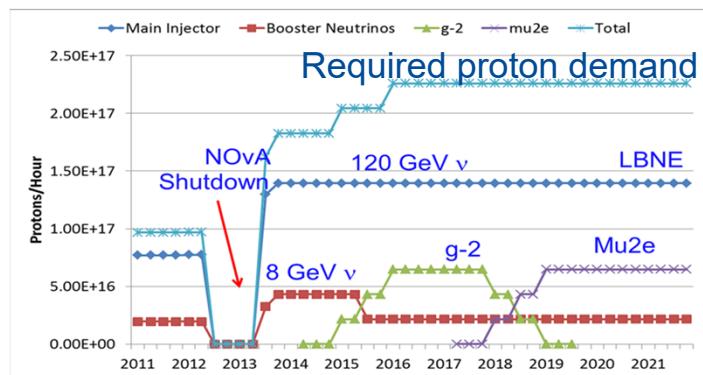
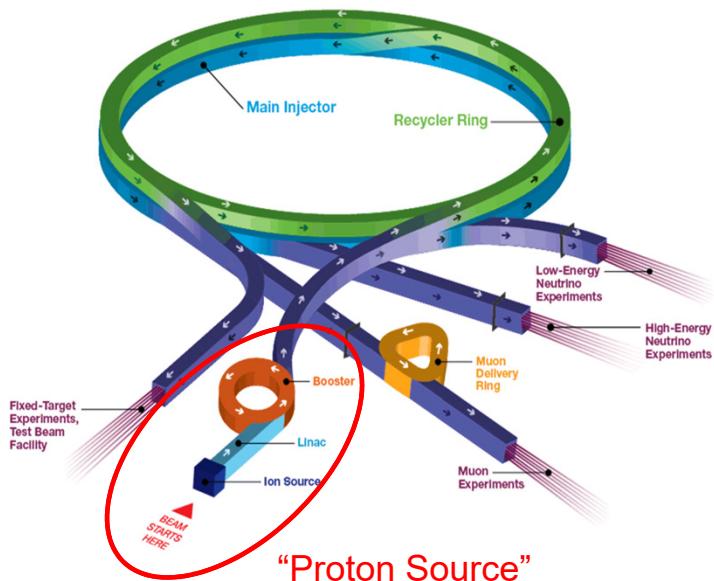
Fermilab Accelerator Complex



# Introduction to Fermilab Accelerators & a Little History

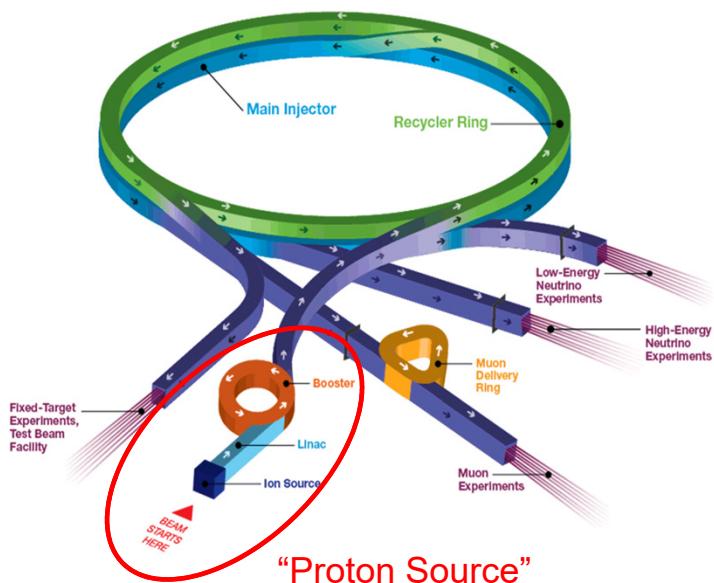
Transitioning from Energy to Intensity Frontier  
First task replacing old Cockcroft-Walton with new RFQ inj. line

Fermilab Accelerator Complex



# Introduction to Fermilab Accelerators & a Little History

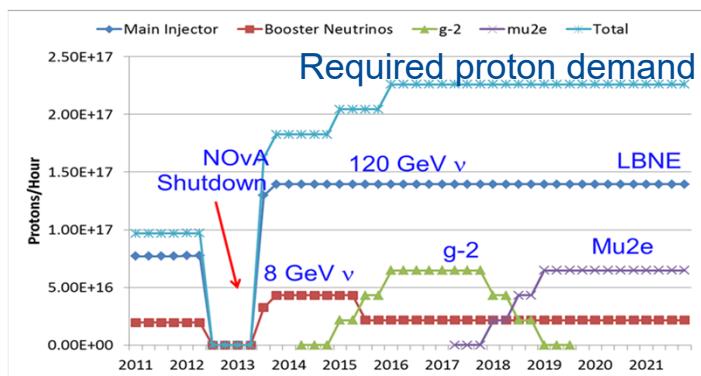
Fermilab Accelerator Complex



## Transitioning from Energy to Intensity Frontier

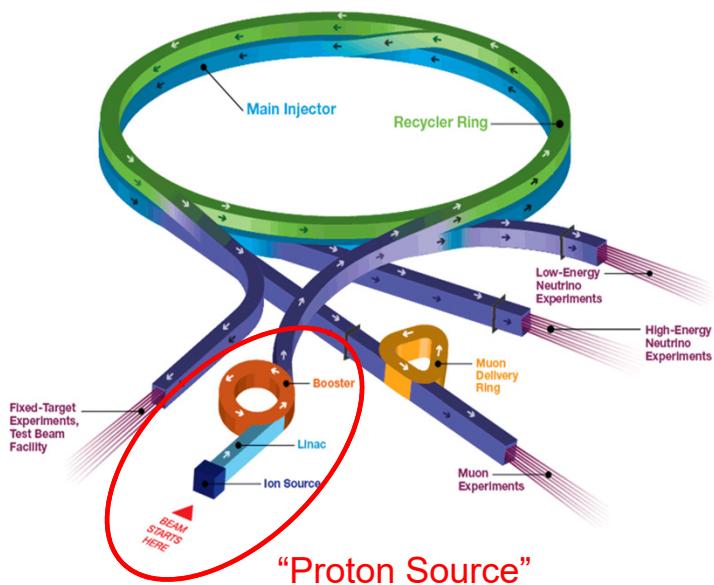
First task replacing old Cockcroft-Walton with new RFQ inj. line

- Proton Improvement Plan (PIP) 2011
  - Double flux without increasing loss
    - From  $\sim 1.1\text{E}17/\text{hr}$  to  $2.25\text{E}17/\text{hr}$  with loss  $< 1\text{W/m}$
  - Up-time (availability)  $> 85\%$
  - Proton Source remain viable to 2025



# Introduction to Fermilab Accelerators & a Little History

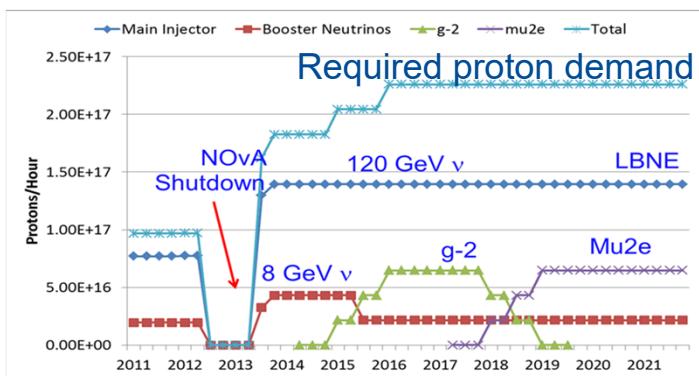
Fermilab Accelerator Complex



## Transitioning from Energy to Intensity Frontier

First task replacing old Cockcroft-Walton with new RFQ inj. line

- Proton Improvement Plan (PIP) 2011
  - Double flux without increasing loss
    - From  $\sim 1.1\text{E}17/\text{hr}$  to  $2.25\text{E}17/\text{hr}$  with loss  $< 1\text{W/m}$
  - Up-time (availability)  $> 85\%$
  - Proton Source remain viable to 2025
- Additional Accelerator Improvements (AIP)
  - Further increase throughput to  $2.7\text{E}17/\text{hr}$  to support 900kW Neutrino running
  - Prepare for PIP-II to come on line in 2028



# Introduction to Proton Source

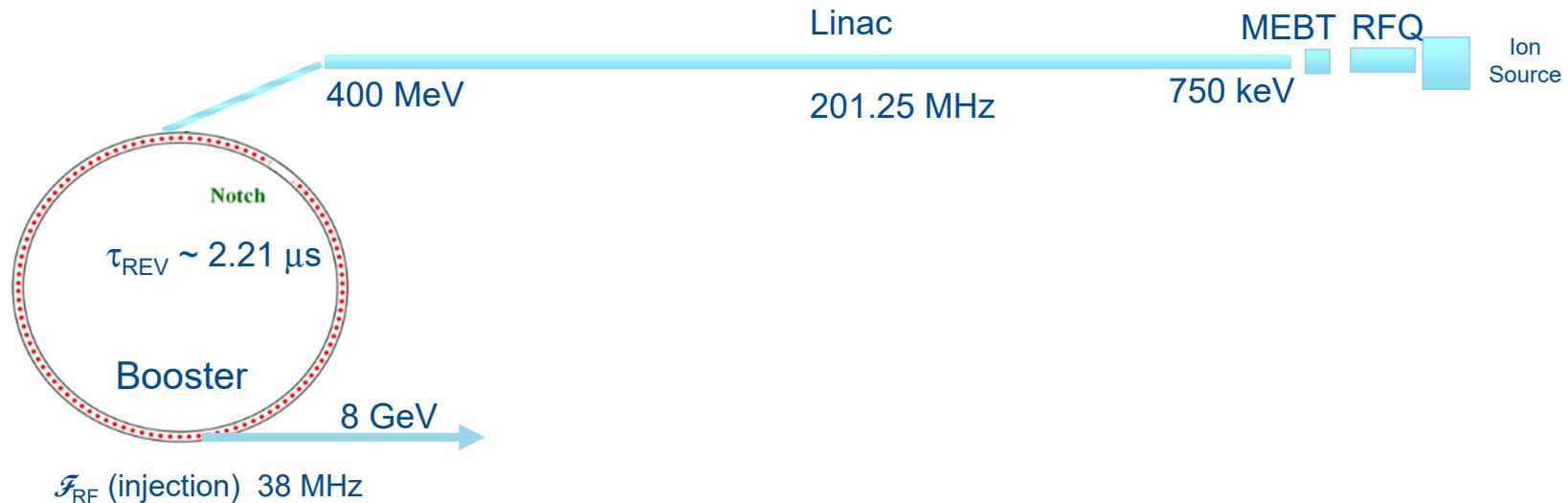
---

—

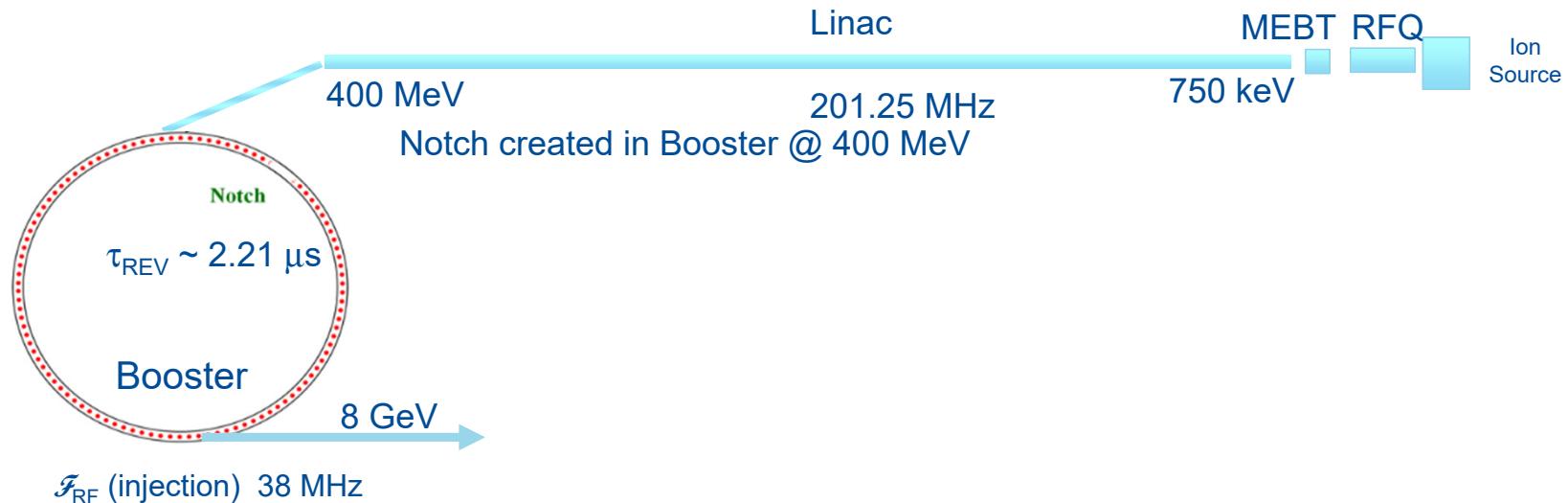
## Introduction to Proton Source



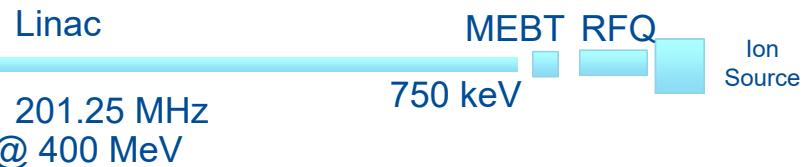
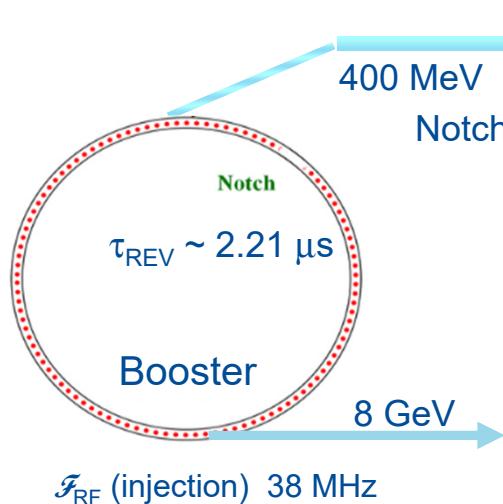
# Introduction to Proton Source



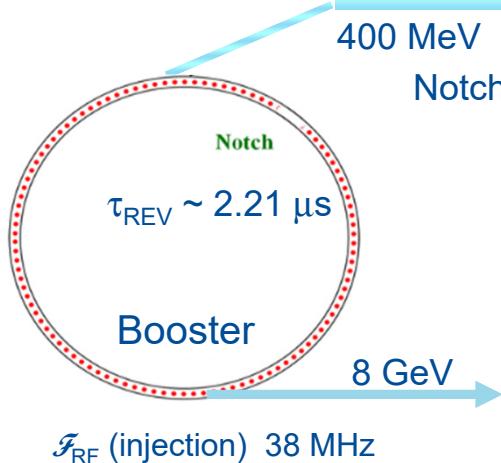
# Introduction to Proton Source



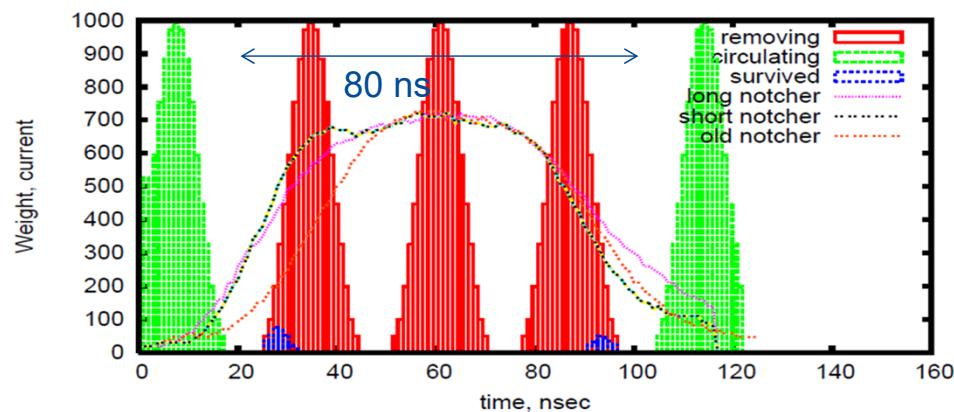
# Introduction to Proton Source



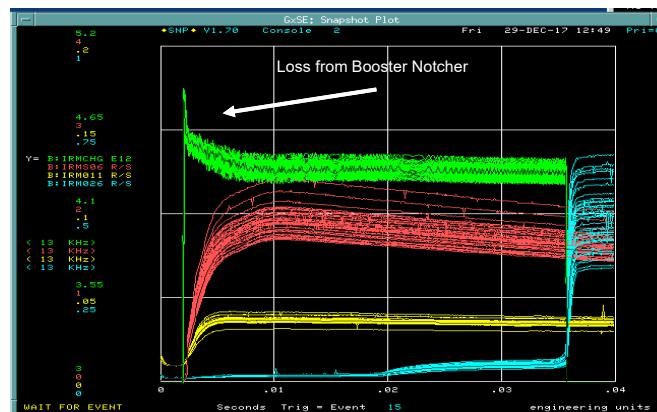
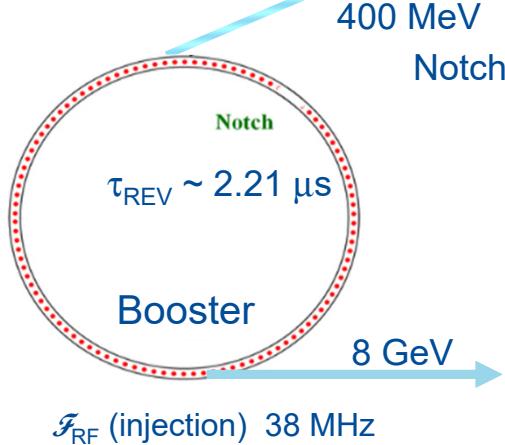
# Introduction to Proton Source



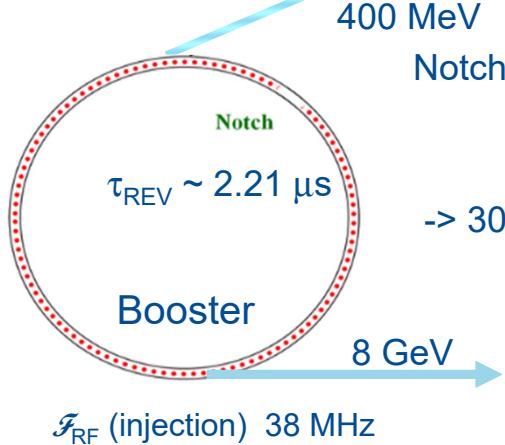
400 MeV  
Notch created in Booster @ 400 MeV



# Introduction to Proton Source



# Introduction to Proton Source

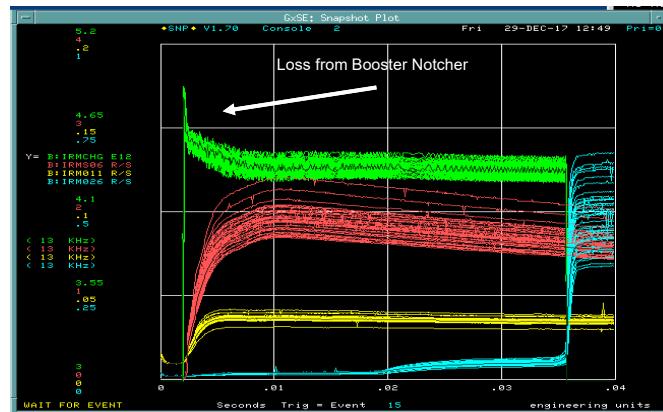


-> 30% total power loss

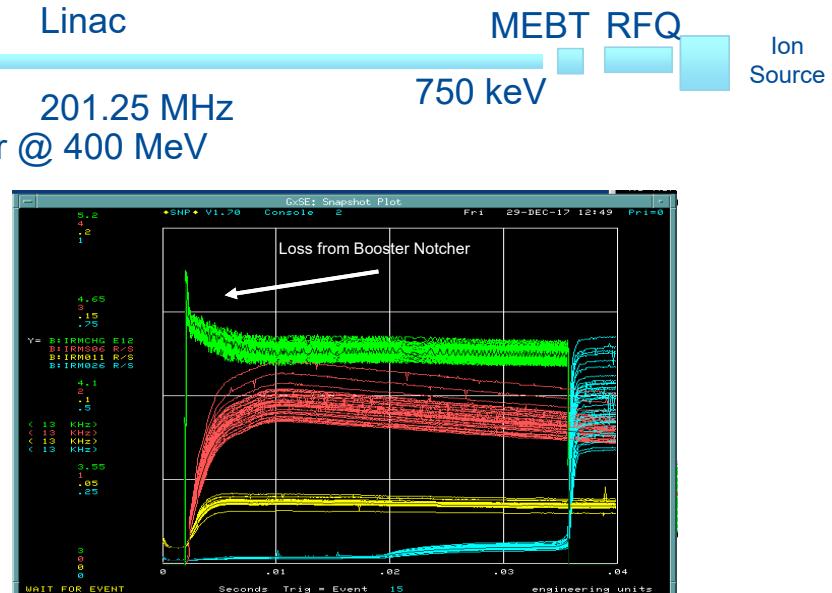
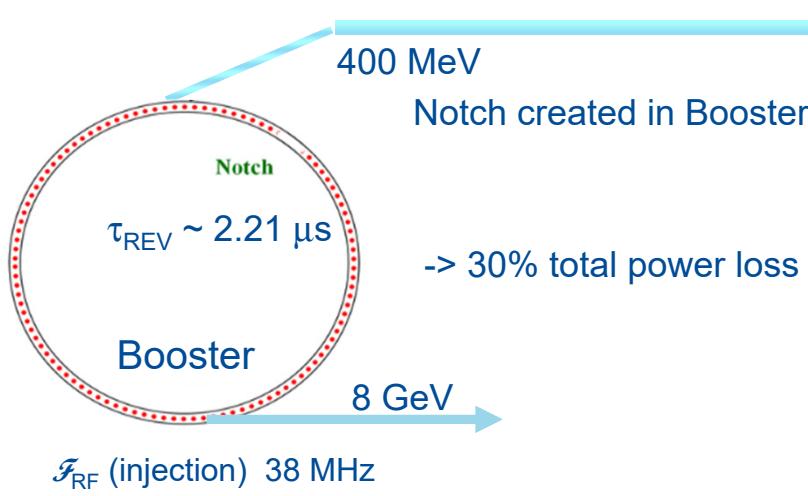
400 MeV  
Notch created in Booster @ 400 MeV

Linac                          MEBT RFQ                  Ion Source

201.25 MHz                  750 keV

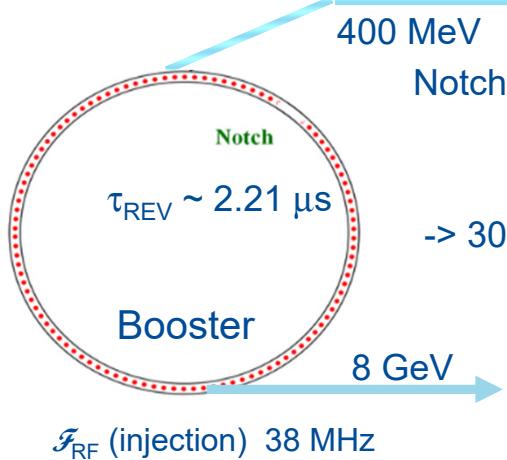


# Introduction to Proton Source



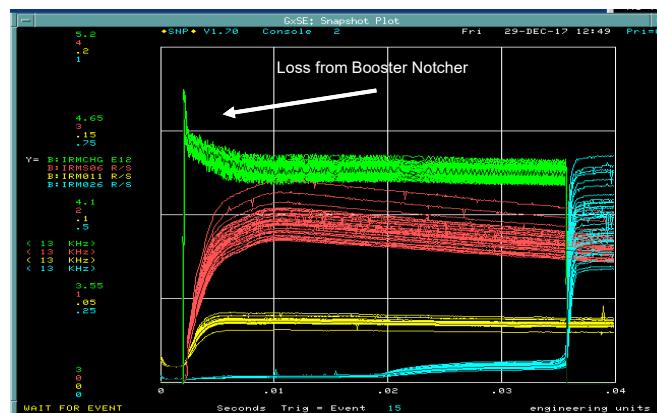
-> Move this process out of the Booster tunnel

# Introduction to Proton Source



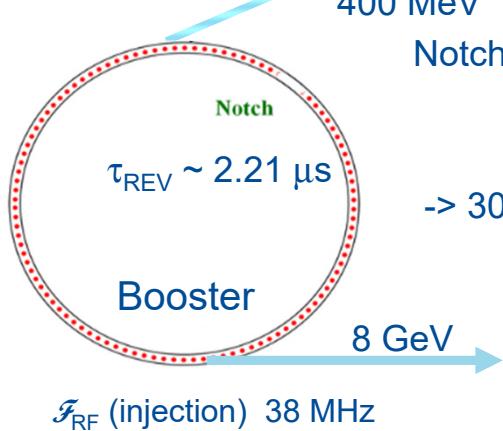
-> 30% total power loss

-> Move this process out of the Booster tunnel



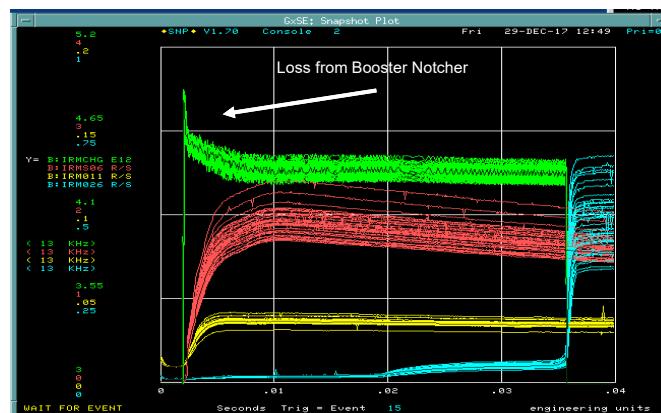
→ Create Notch in linac at 750 keV

# Introduction to Proton Source



-> 30% total power loss

-> Move this process out of the Booster tunnel

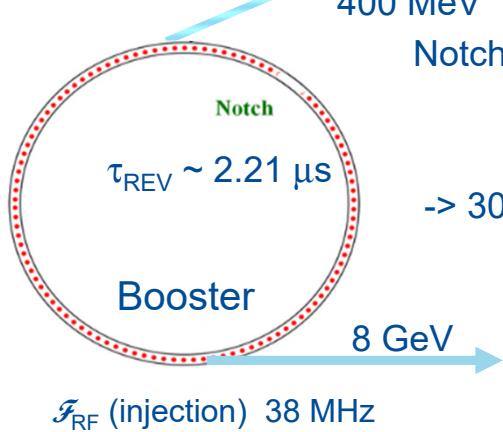


→ Create Notch in linac at 750 keV



LINAC PULSE

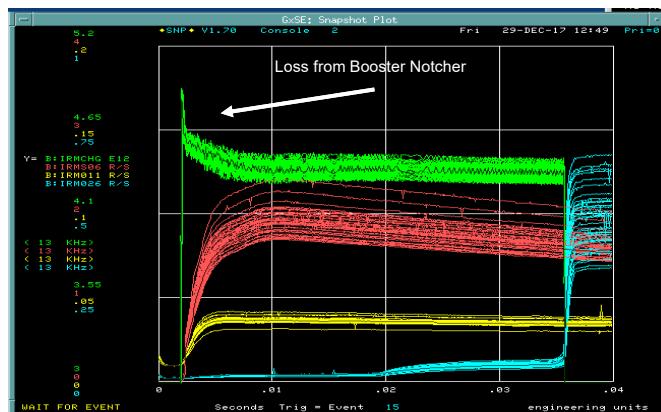
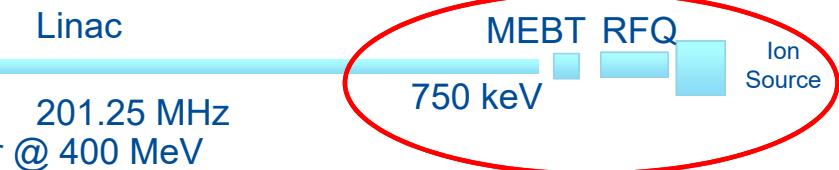
# Introduction to Proton Source



400 MeV  
Notch created in Booster @ 400 MeV

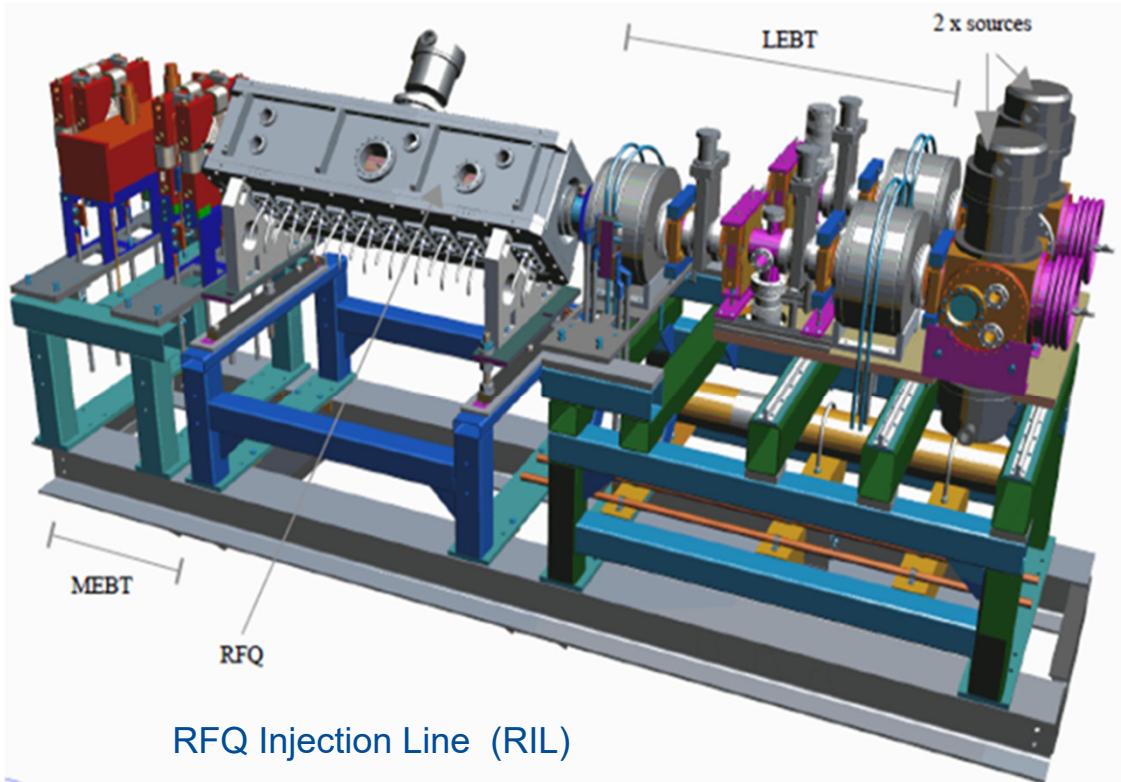
-> 30% total power loss

-> Move this process out of the Booster tunnel

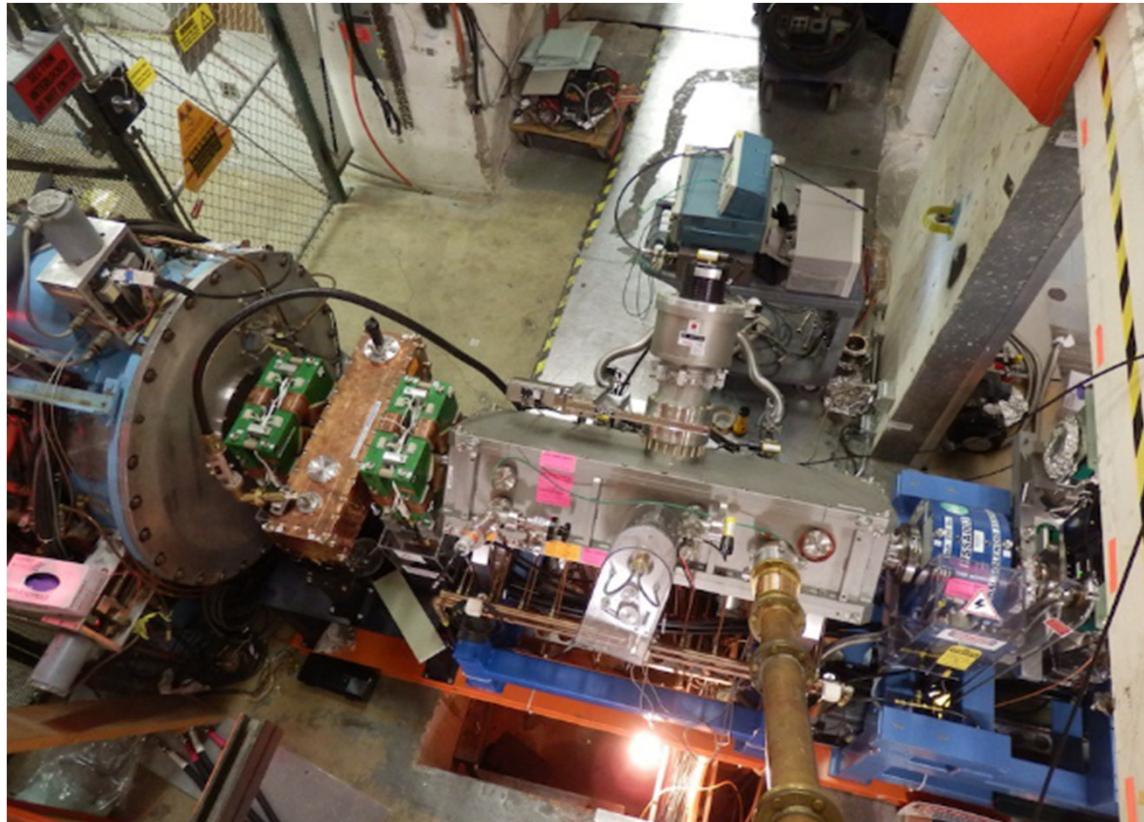


→ Create Notch in linac at 750 keV

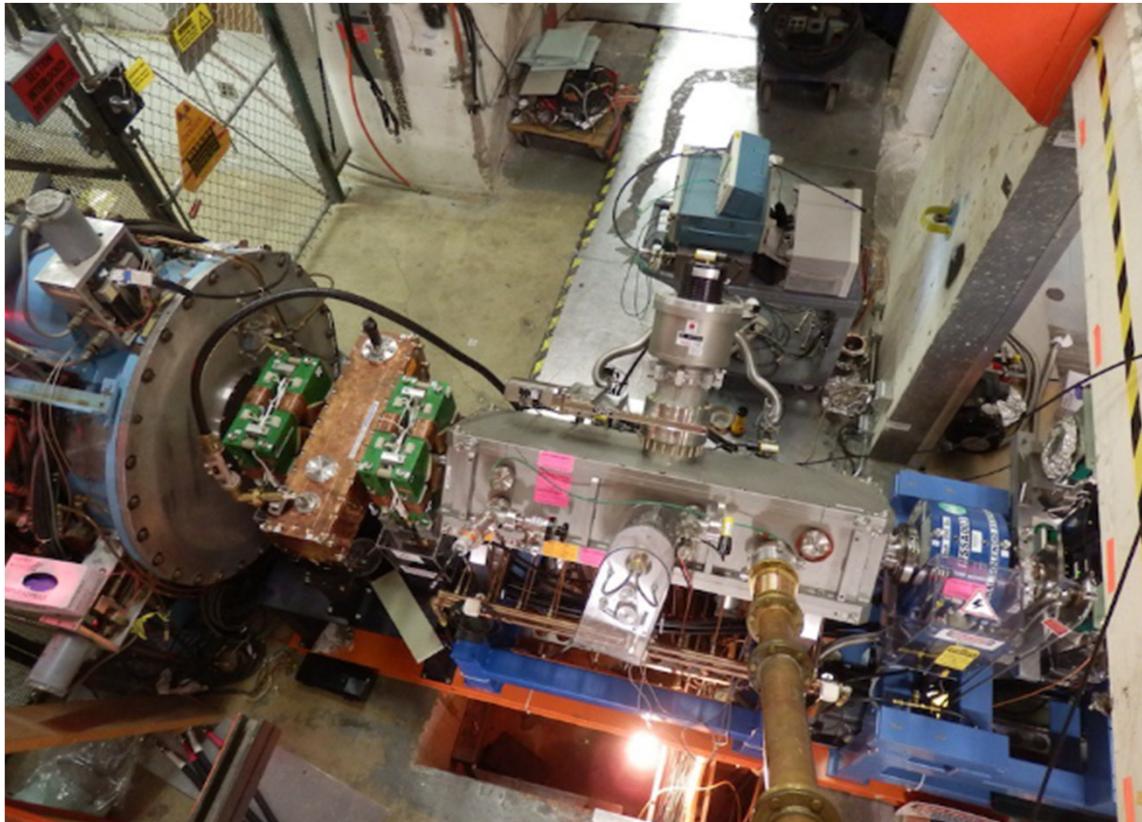
## Introduction to Proton Source: the New Linac RFQ Injection Line (space constraints)



## Introduction to Proton Source: the New Linac RFQ Injection Line (space constraints)



## Introduction to Proton Source: the New Linac RFQ Injection Line (space constraints)



Standard E&M kicker  
->Not enough space

## Introduction to Proton Source: the New Linac RFQ Injection Line (space constraints)



Standard E&M kicker  
->Not enough space

## Introduction to Proton Source: the New Linac RFQ Injection Line (space constraints)



Standard E&M kicker  
->Not enough space

A R&D project was included in PIP to develop a laser system to create the required notches in the linac pulse and could fit into the very tight space constraints.

## Technique: Photoneutralization

---

## Technique: Photoneutralization

---

$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{\text{crossing}}})$$

## Technique: Photoneutralization

---

$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

## Technique: Photoneutralization

---

$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

✓ Want to make process efficient

## Technique: Photoneutralization

---

$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

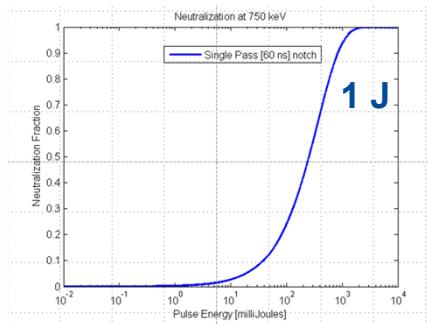
- ✓ Want to make process efficient ➔ minimize required laser pulse energy/average power

## Technique: Photoneutralization

$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

- ✓ Want to make process efficient → minimize required laser pulse energy/average power

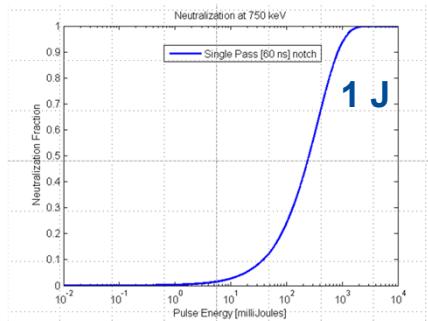


## Technique: Photoneutralization

$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

- ✓ Want to make process efficient → minimize required laser pulse energy/average power



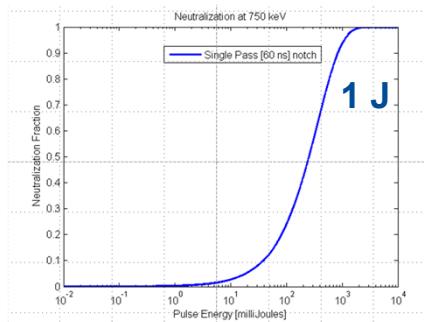
➤ Match laser pulses to bunch parameters

## Technique: Photoneutralization

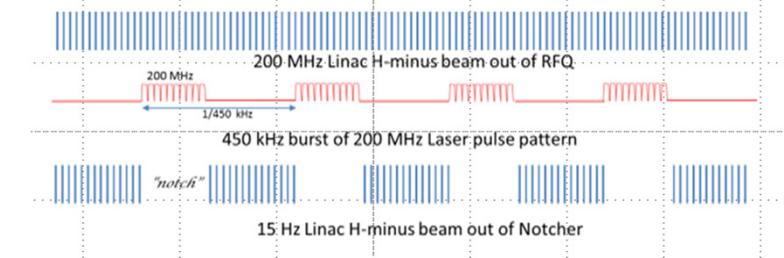
$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

- ✓ Want to make process efficient → minimize required laser pulse energy/average power



➤ Match laser pulses to bunch parameters

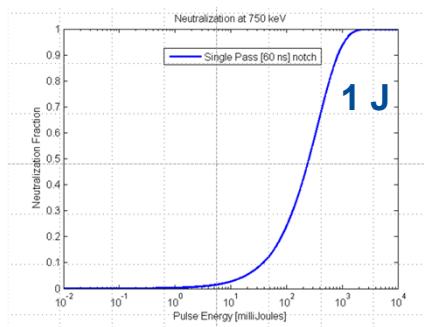


## Technique: Photoneutralization

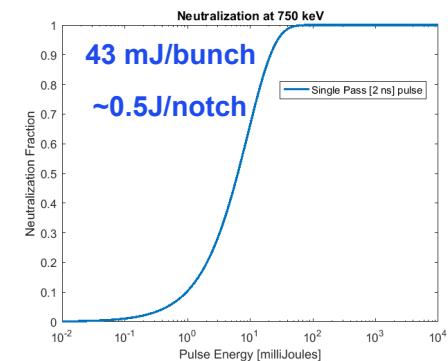
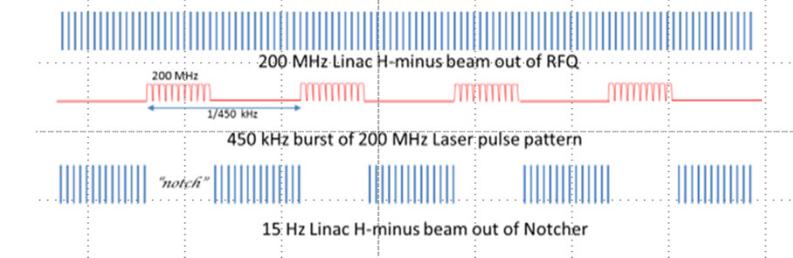
$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

- ✓ Want to make process efficient ➔ minimize required laser pulse energy/average power



➤ Match laser pulses to bunch parameters

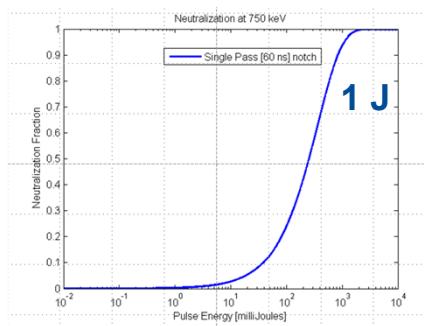


## Technique: Photoneutralization

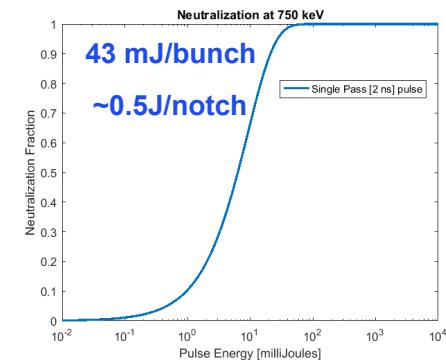
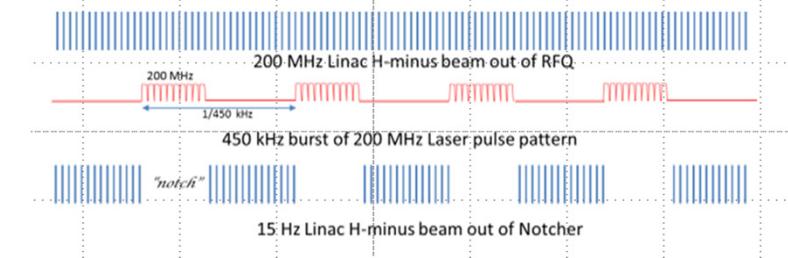
$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

- ✓ Want to make process efficient → minimize required laser pulse energy/average power



➤ Match laser pulses to bunch parameters



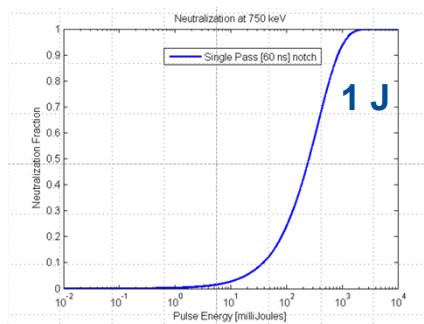
➤ Non-resonant optical cavity (we call a zig-zag cavity)

## Technique: Photoneutralization

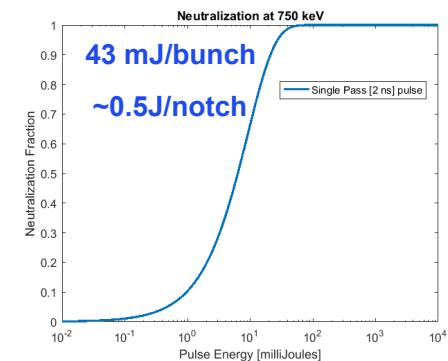
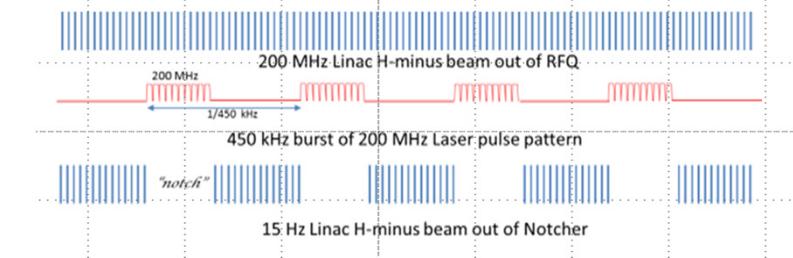
$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

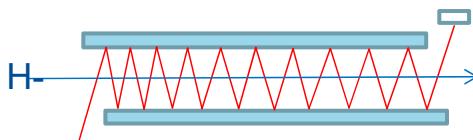
- ✓ Want to make process efficient ➔ minimize required laser pulse energy/average power



➤ Match laser pulses to bunch parameters



➤ Non-resonant optical cavity (we call a zig-zag cavity)

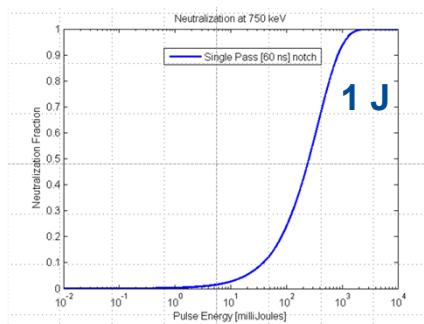


## Technique: Photoneutralization

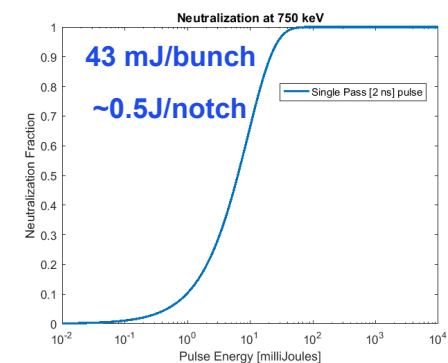
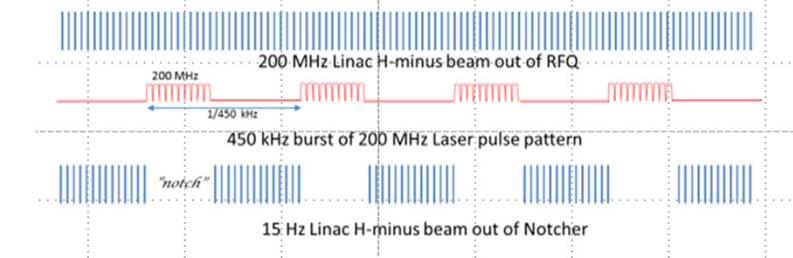
$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

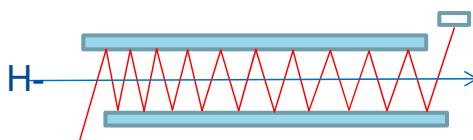
- ✓ Want to make process efficient → minimize required laser pulse energy/average power



➤ Match laser pulses to bunch parameters



➤ Non-resonant optical cavity (we call a zig-zag cavity)



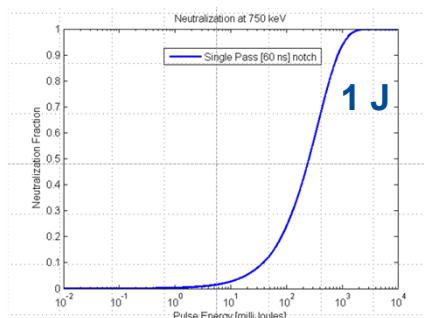
$$F_N = 1 - (1 - F_{neut})^N$$

## Technique: Photoneutralization

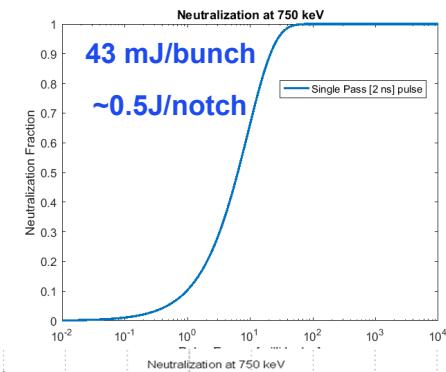
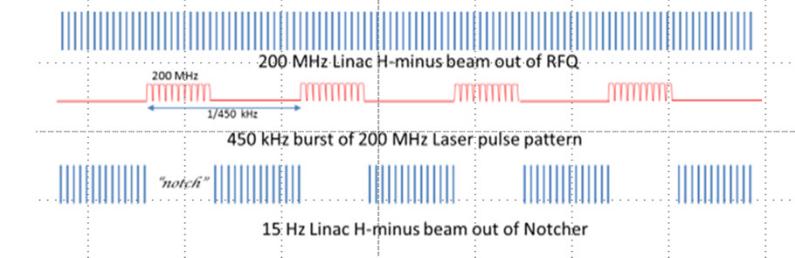
$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

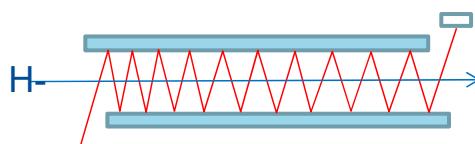
✓ Want to make process efficient ➔ minimize required laser pulse energy/average power



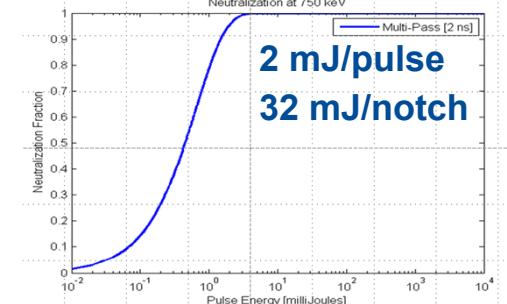
➤ Match laser pulses to bunch parameters



➤ Non-resonant optical cavity (we call a zig-zag cavity)



$$F_N = 1 - (1 - F_{neut})^N$$

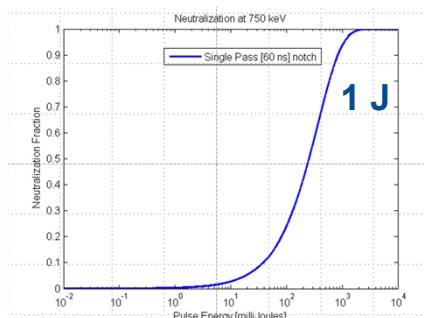


## Technique: Photoneutralization

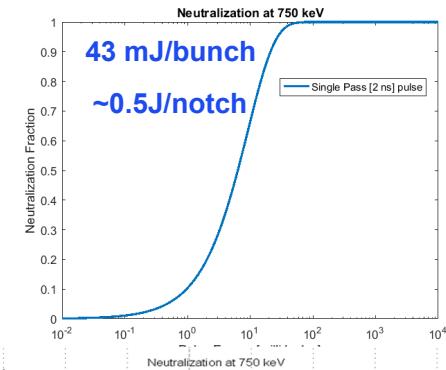
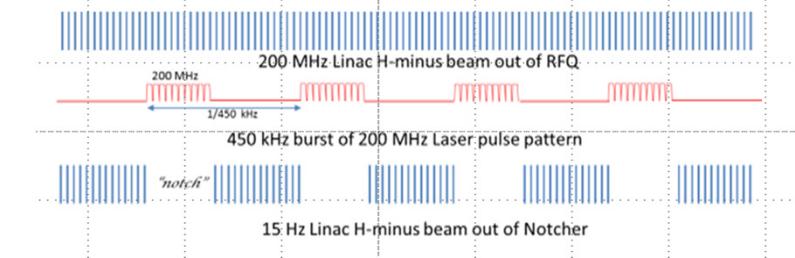
$$F_1 = \frac{N}{N_0} = (1 - e^{-f_{CM} * \sigma(E) * \tau_{crossing}})$$

➤ 1 micron laser- near peak of cross section

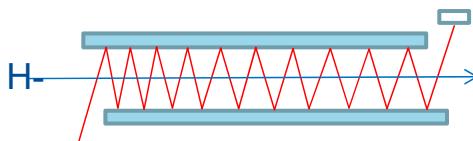
✓ Want to make process efficient ➔ minimize required laser pulse energy/average power



➤ Match laser pulses to bunch parameters

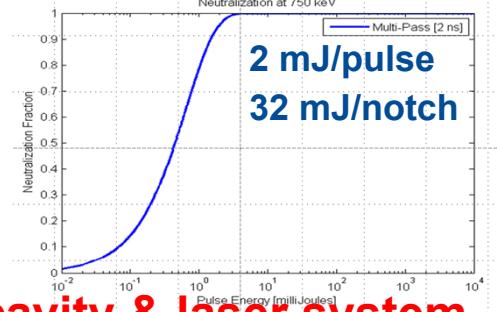


➤ Non-resonant optical cavity (we call a zig-zag cavity)

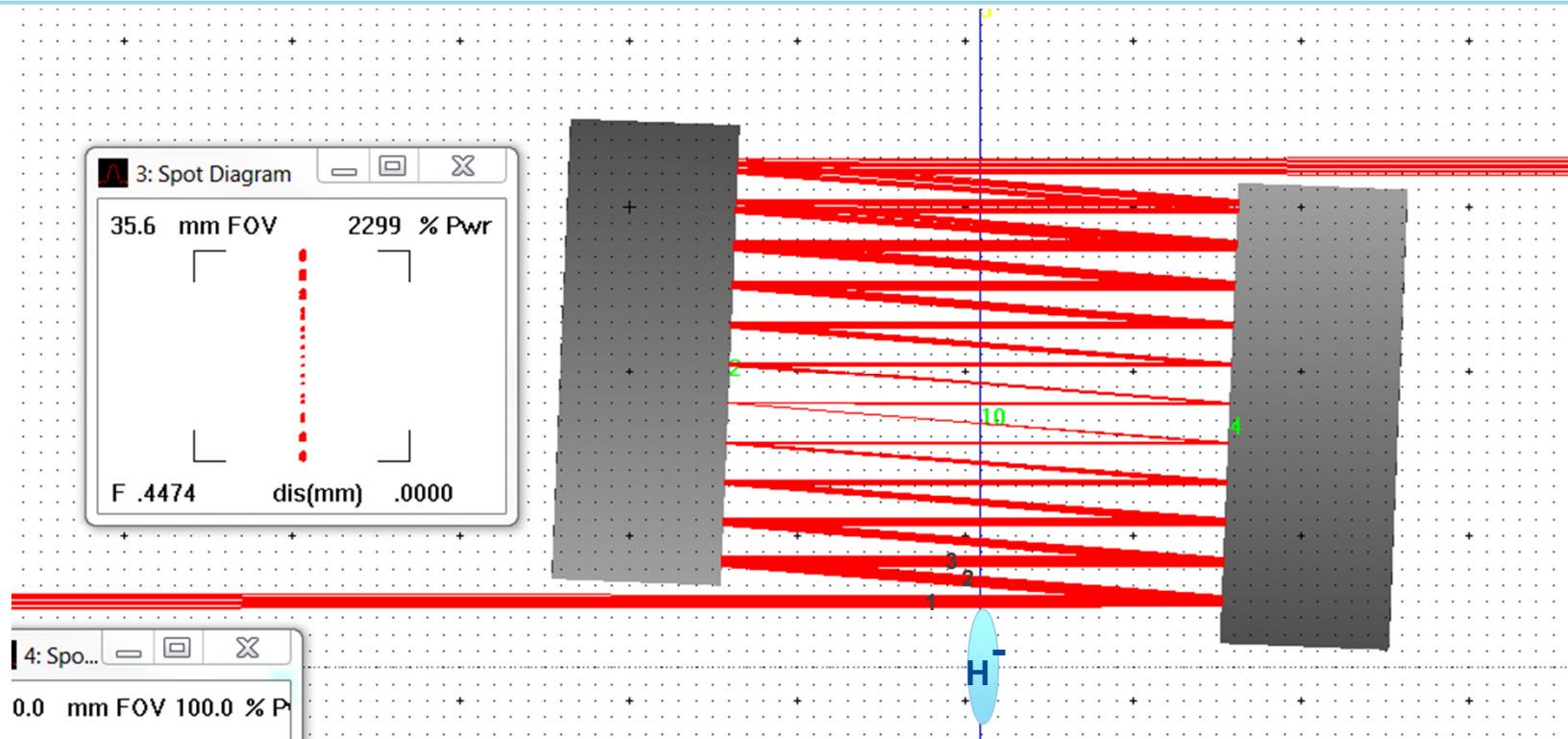


$$F_N = 1 - (1 - F_{neut})^N$$

➤ We needed to develop 2 components: interaction cavity & laser system

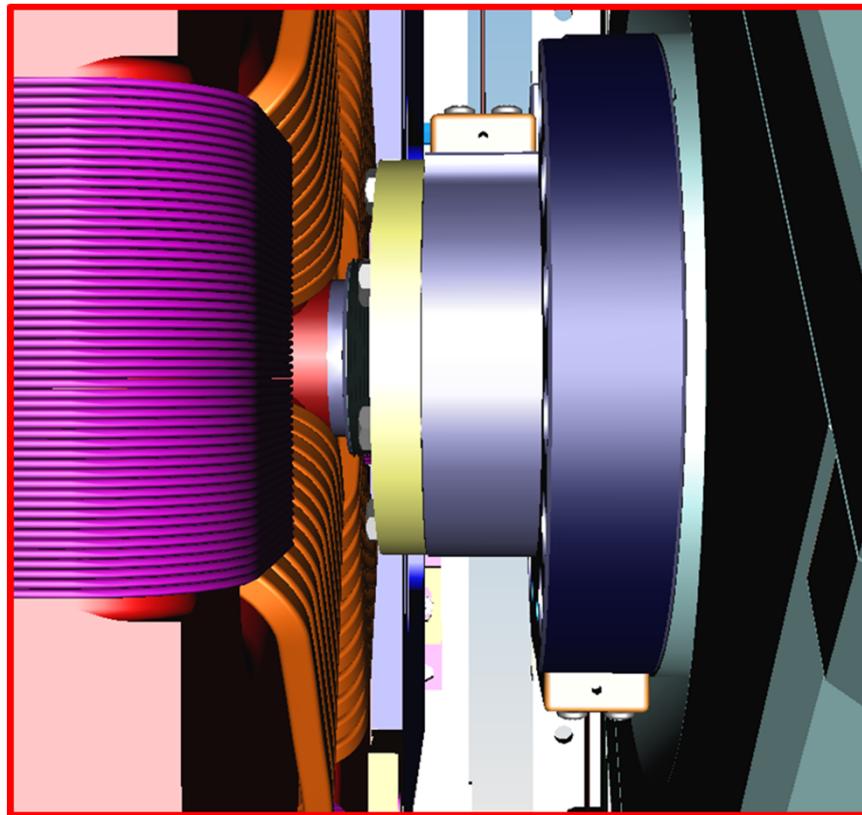


## Interaction Cavity: Concept

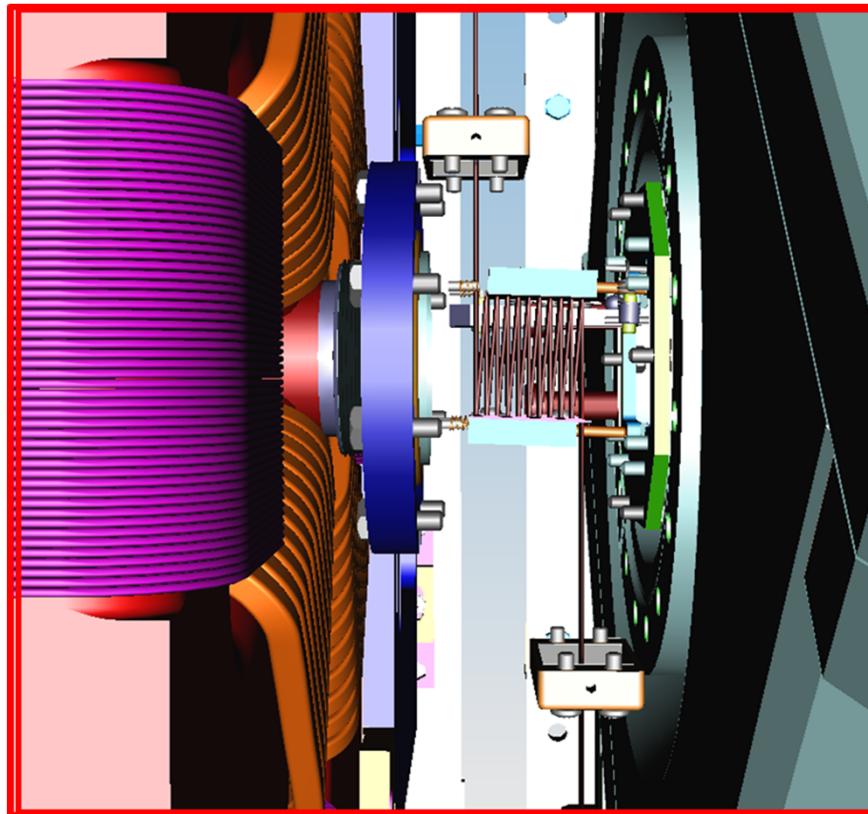


- Match velocities of laser propagation down the cavity with velocity of ion bunch.
- Laser pulse length match ion bunch length

## Interaction Cavity: Development

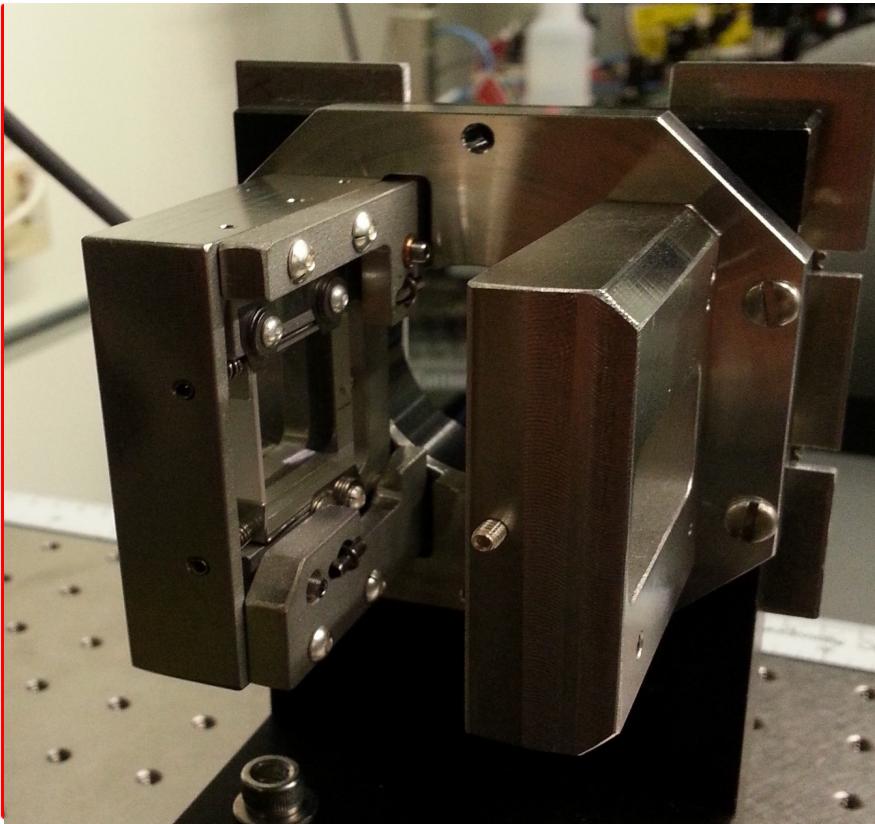


## Interaction Cavity: Development



## Interaction Cavity: Development

---



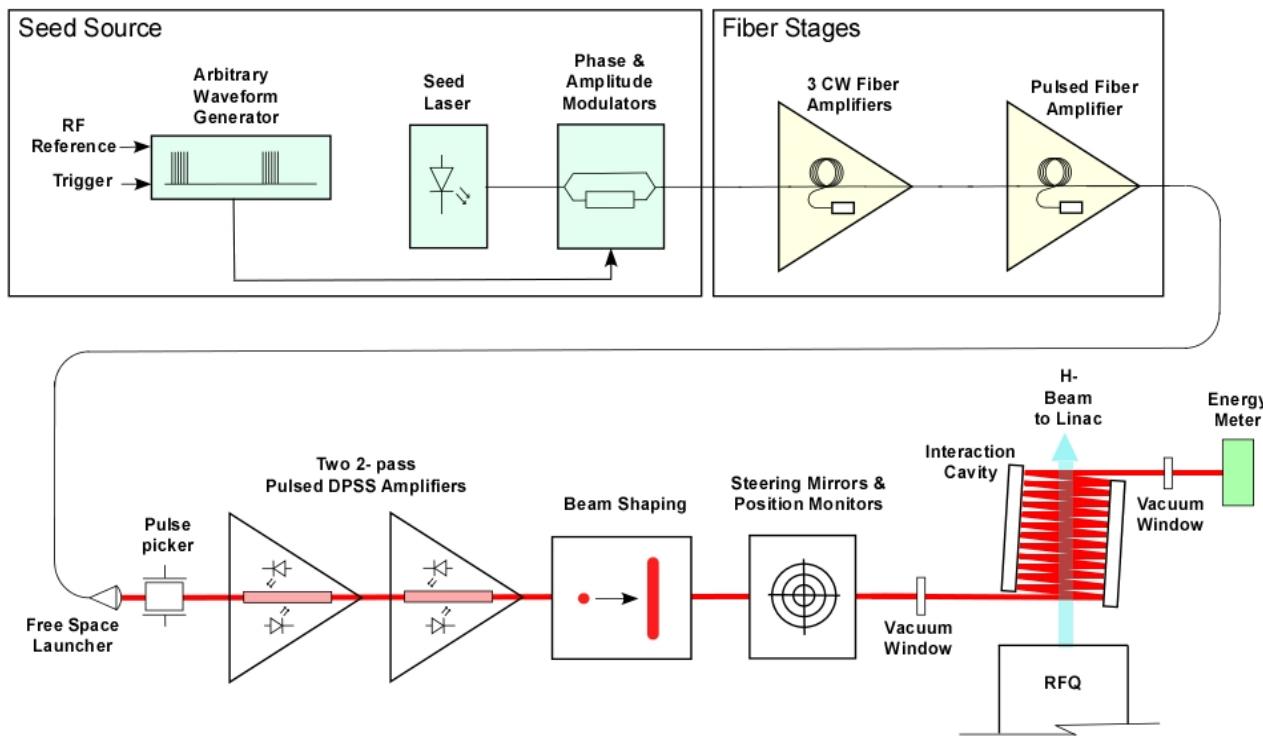
## Interaction Cavity: Development



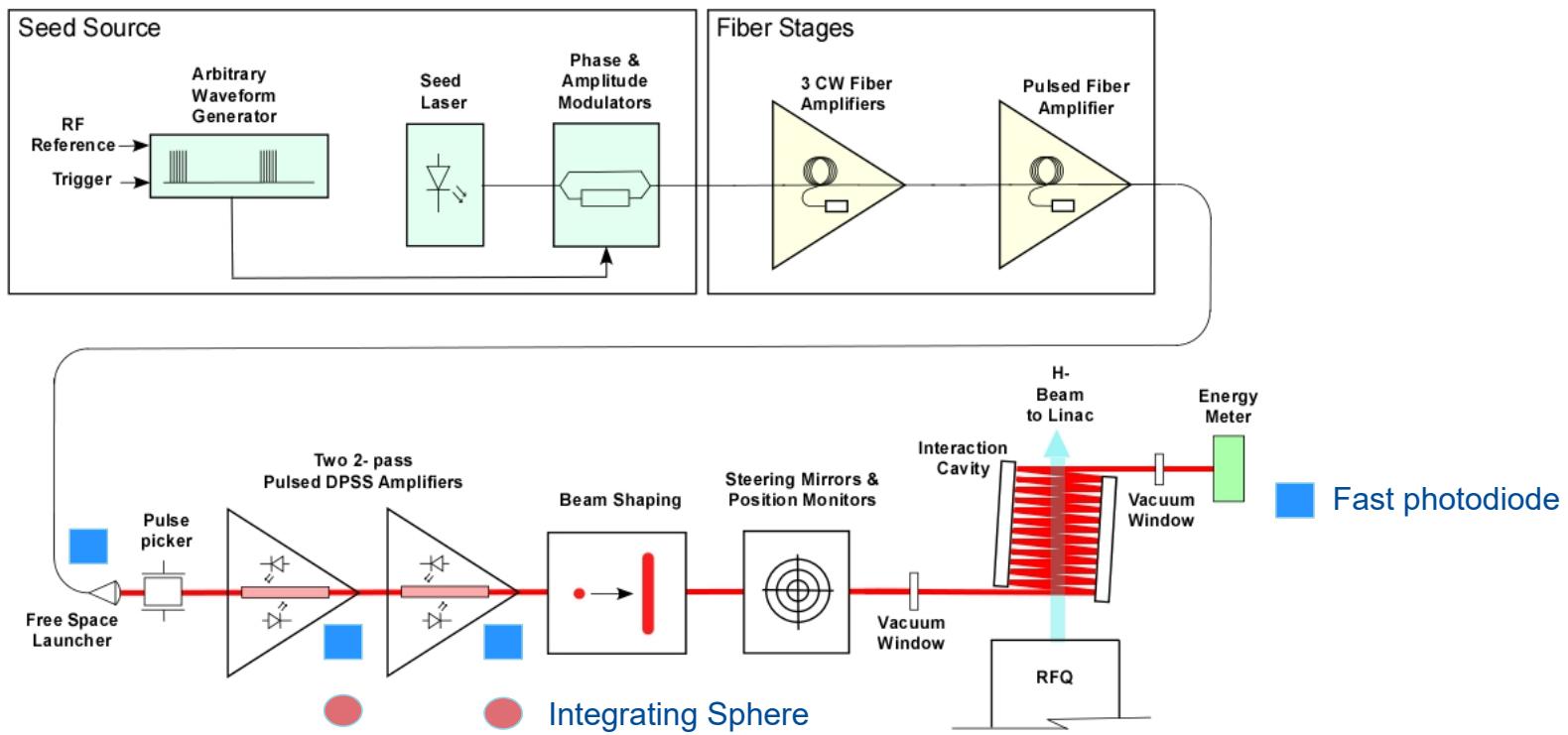
## Laser System: Design

---

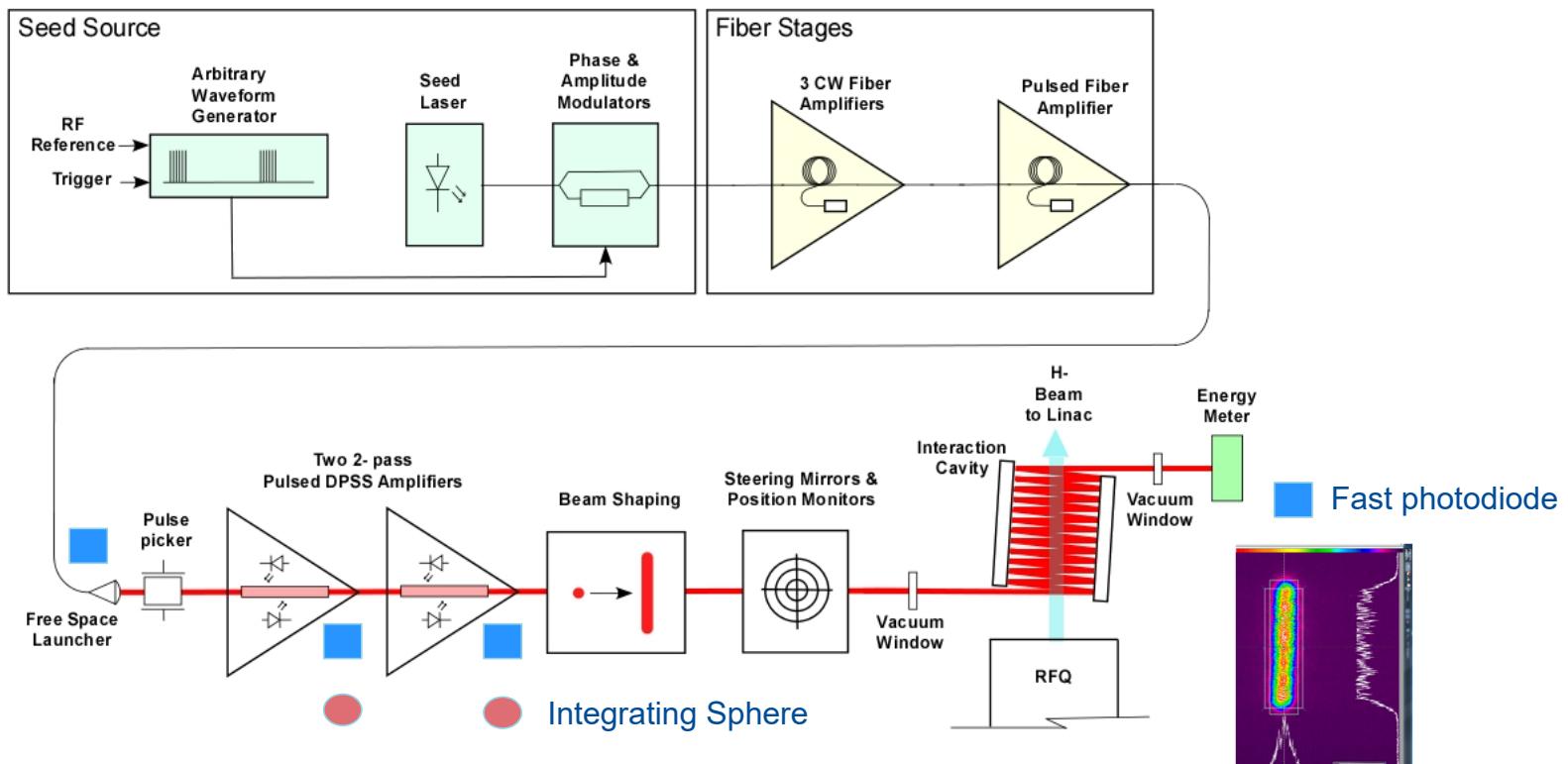
# Laser System: Design



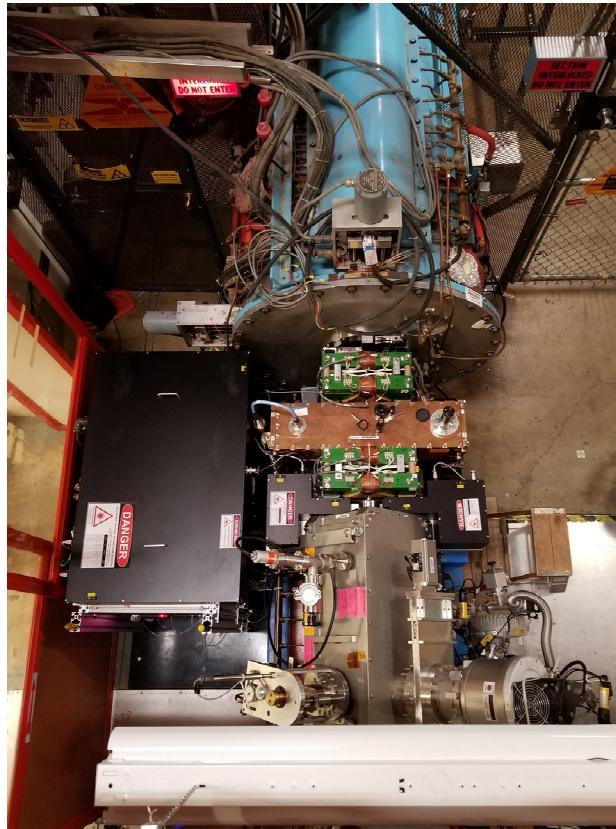
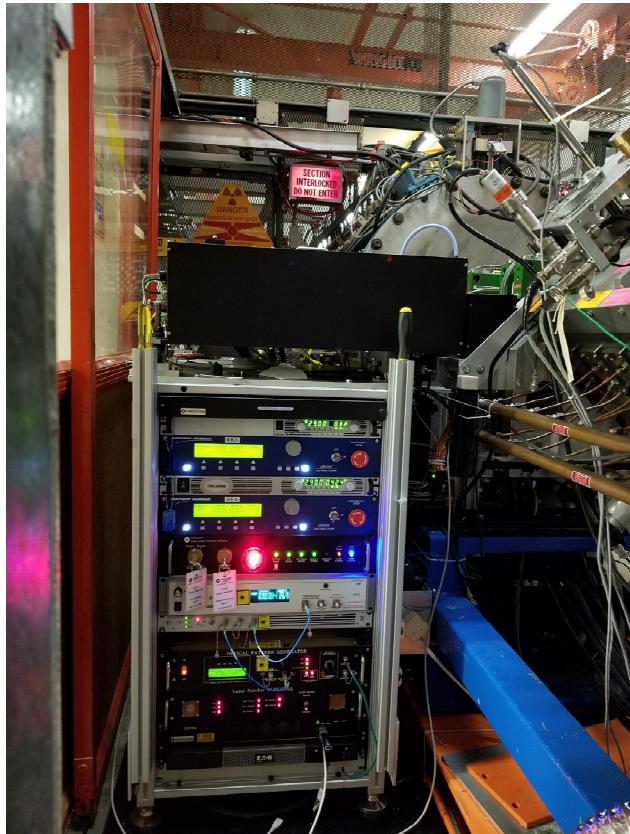
# Laser System: Design



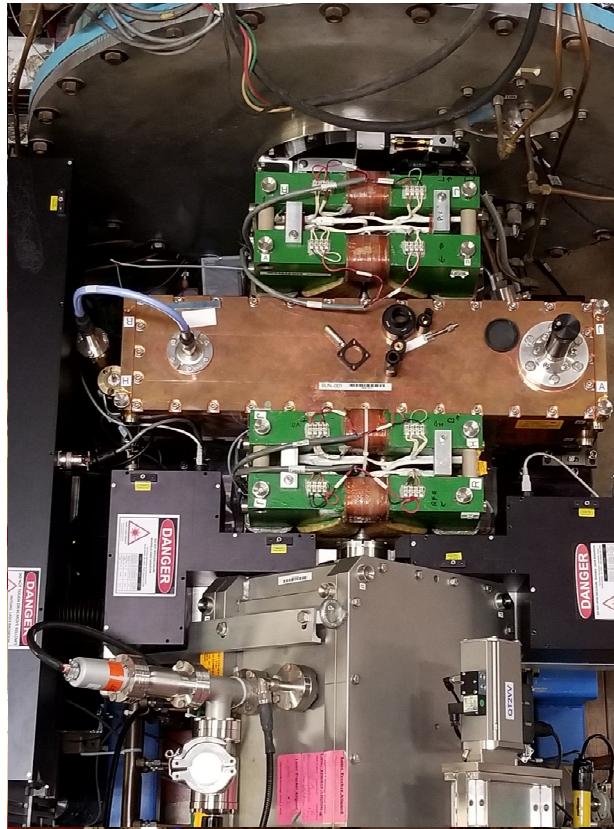
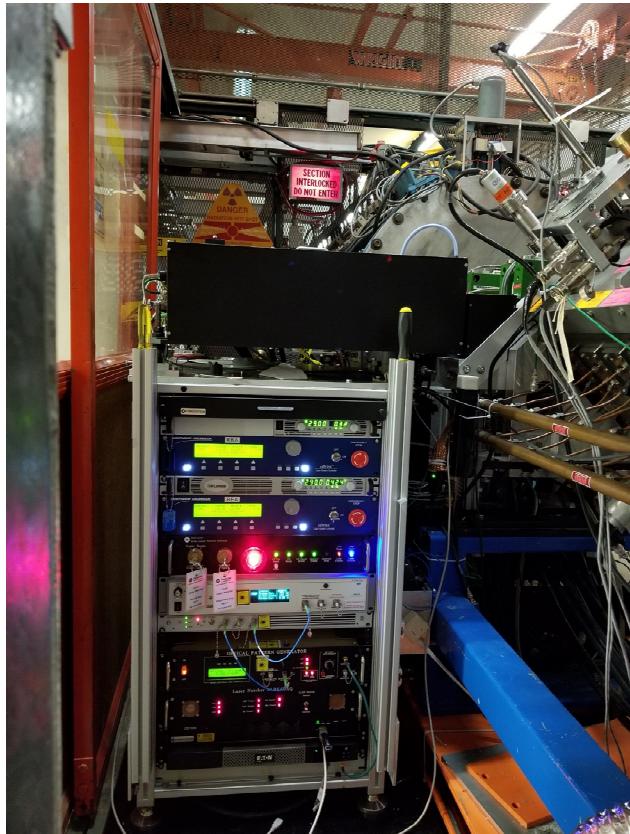
# Laser System: Design



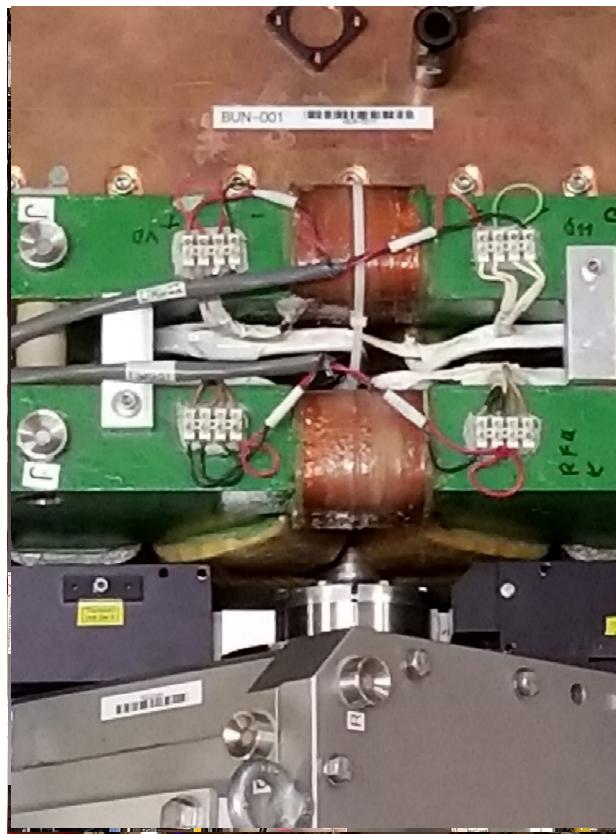
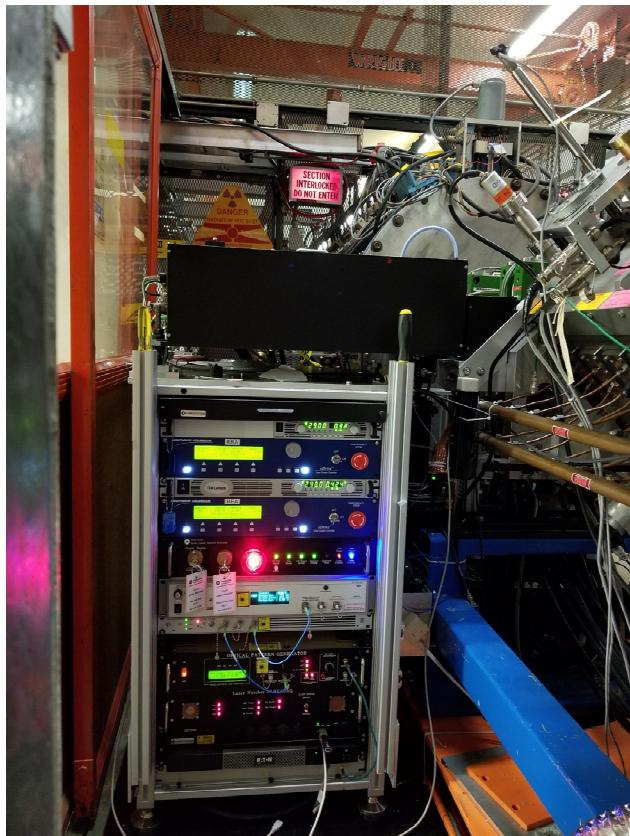
## Operational Laser System Installed in Linac



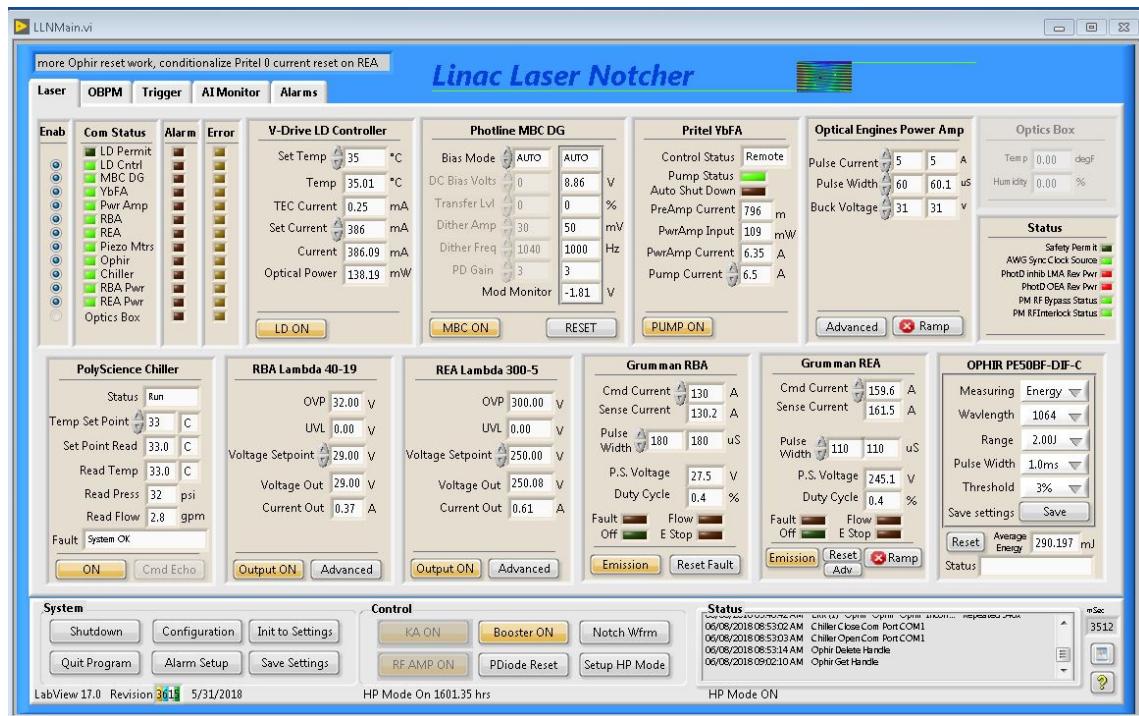
## Operational Laser System Installed in Linac



## Operational Laser System Installed in Linac

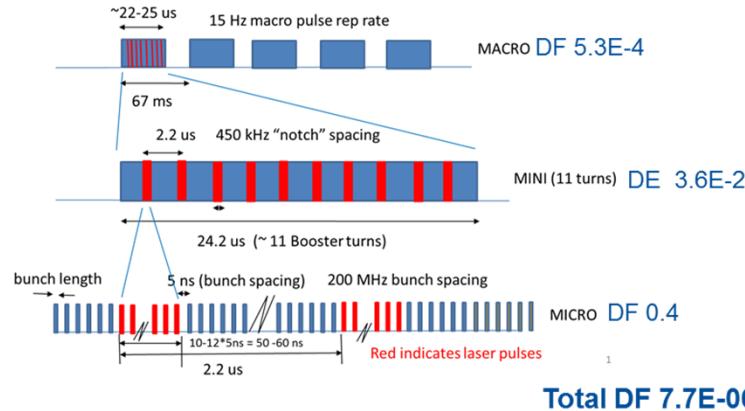


# Laser System: Controls

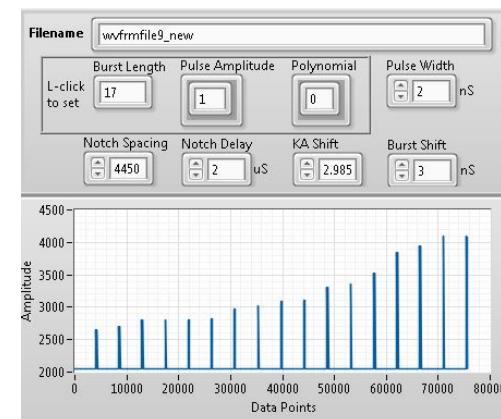
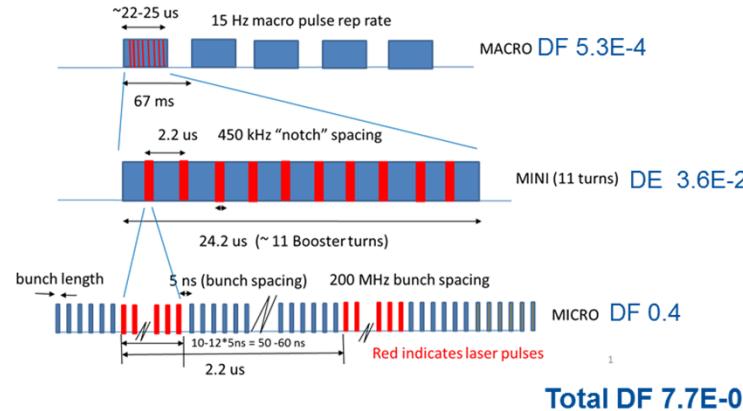


- Flexible que driven state machine
- GUI interface, ACNET communication, hardware monitoring, and state machine – ALL INDEPENDENT tasks
- Real time configurable alarms
- Robust setting, monitoring(configuration and communication) display and logging
  - Configurable mail reports
- Settable range constraints for all control inputs
- Very flexible waveform creation
- Main Operations interface through ACNET parameter page and JAVA web monitor page

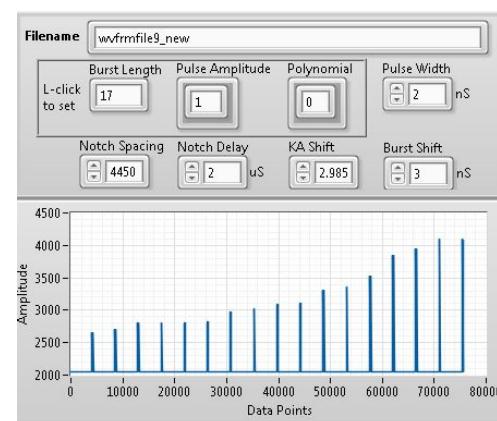
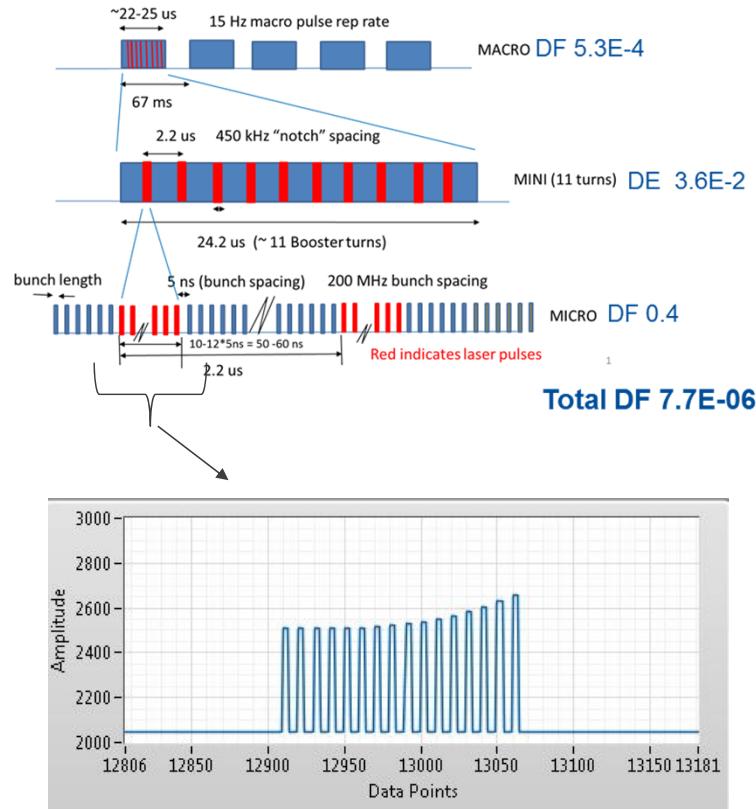
# Laser System: Arbitrary Waveform Generation



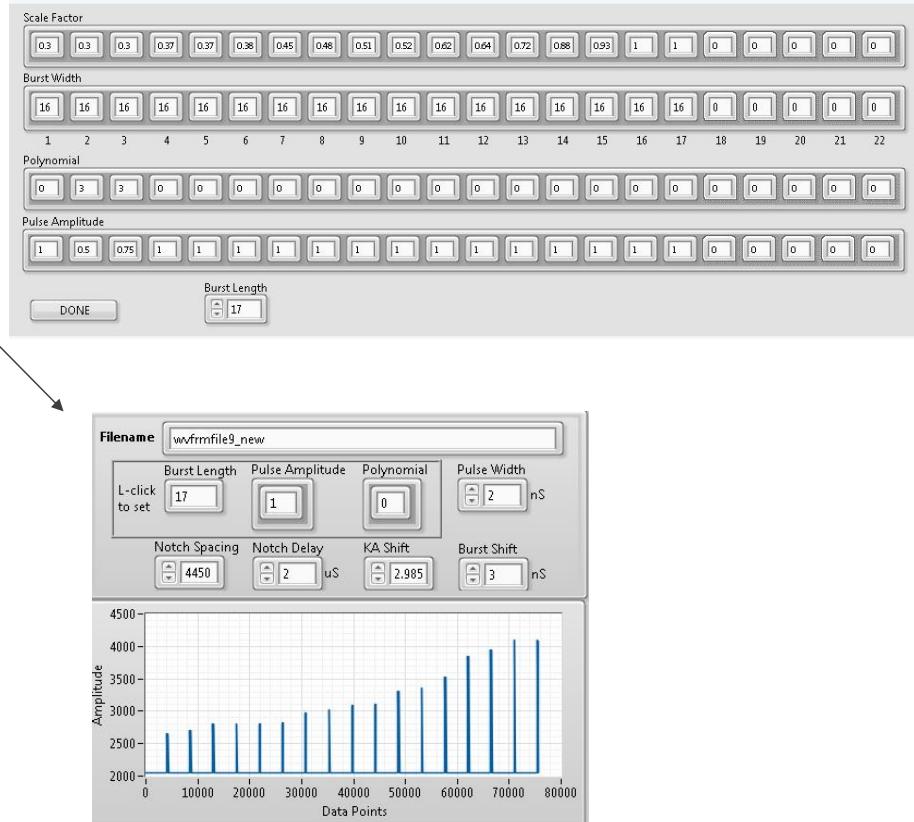
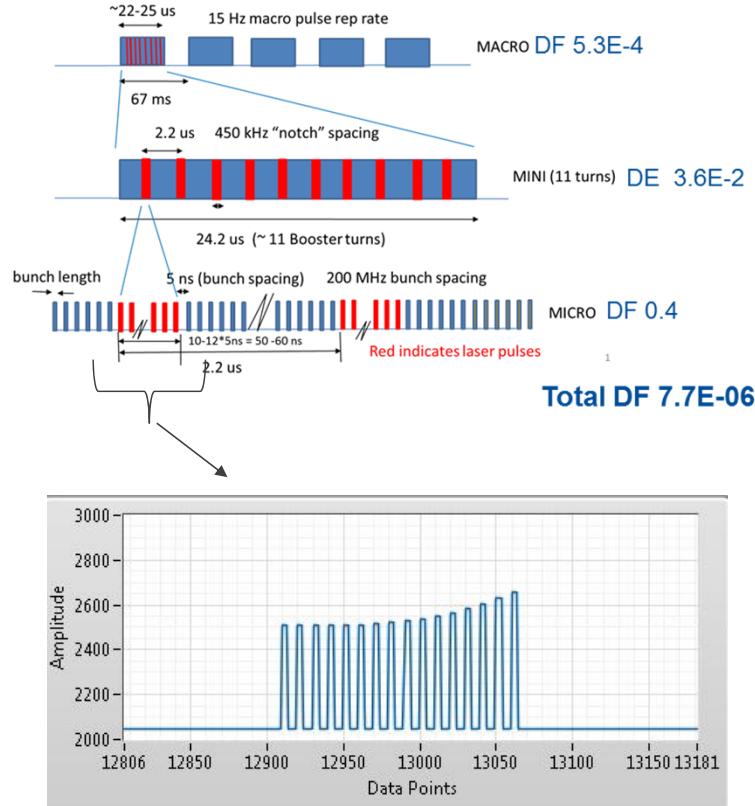
# Laser System: Arbitrary Waveform Generation



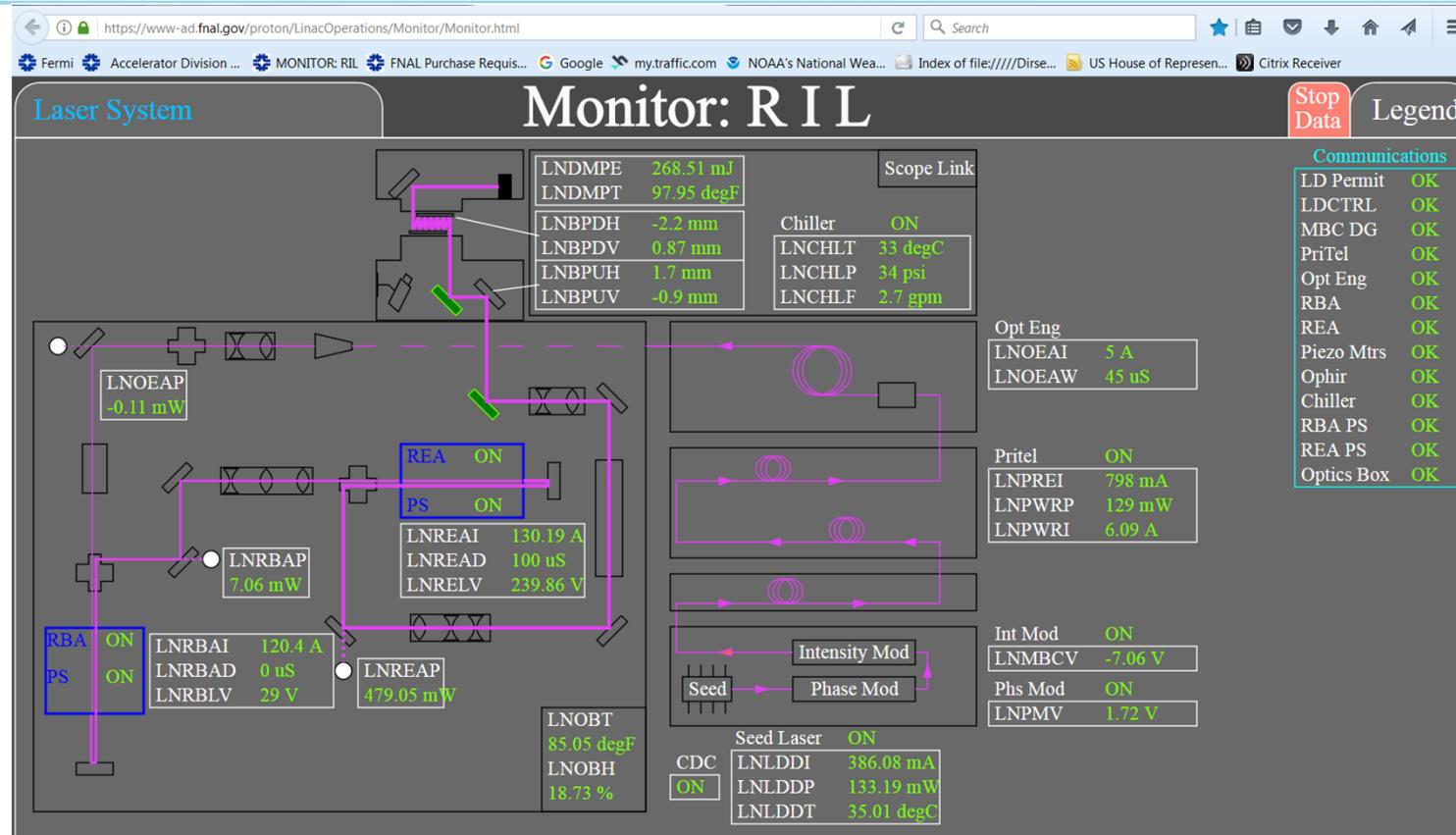
# Laser System: Arbitrary Waveform Generation



# Laser System: Arbitrary Waveform Generation

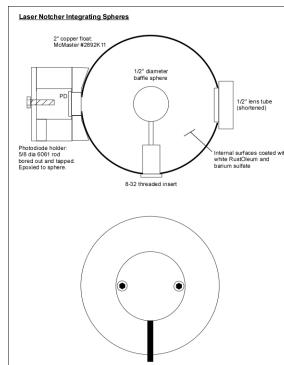


# Laser System: Operational System Monitoring

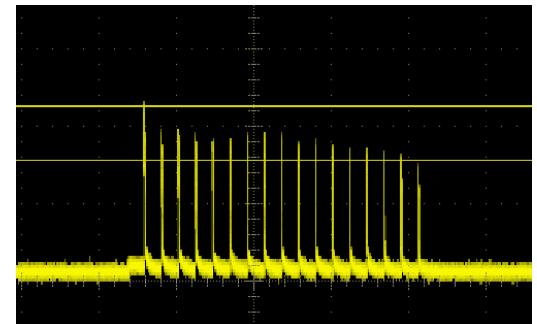
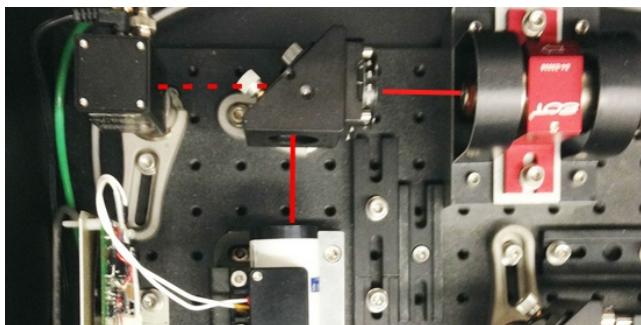


## Laser System: Instrumentation in Optics Box

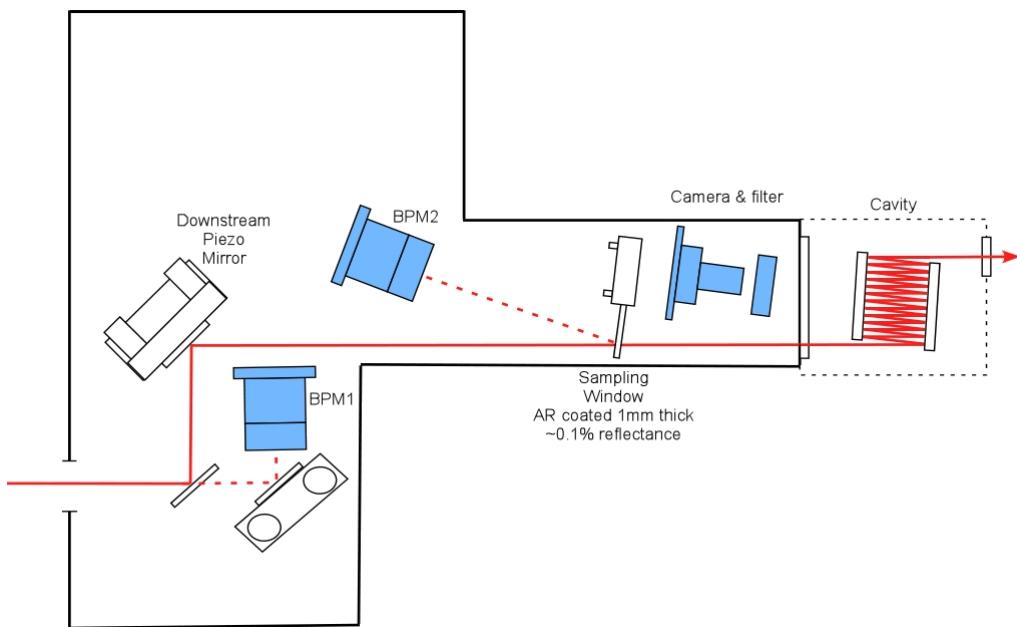
- Integrating Sphere (developed @ FNAL)



- Photodiode (commercial)

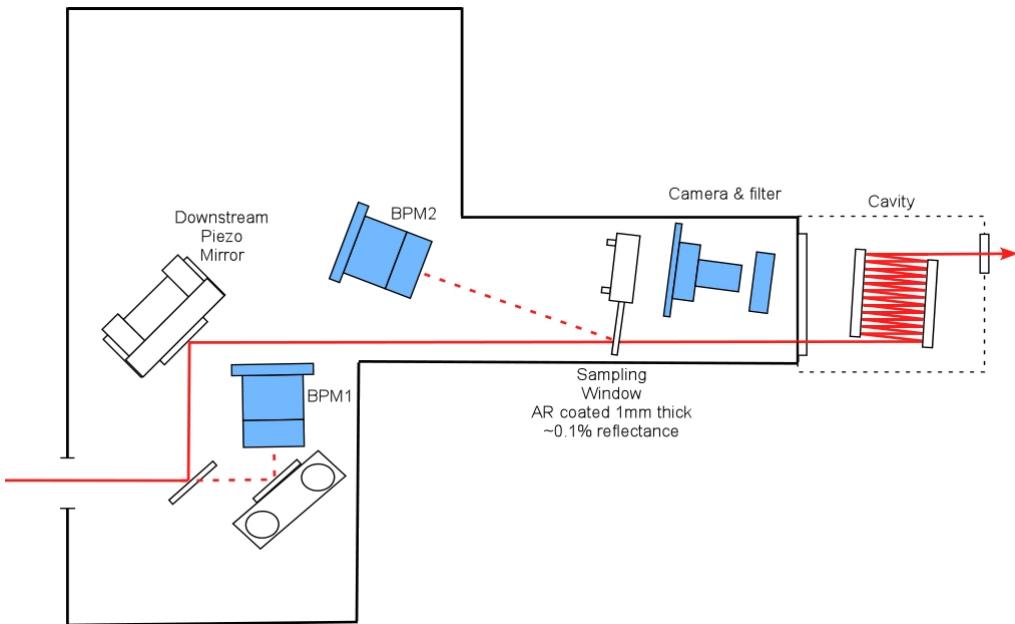


## Laser System: Transport Enclosure



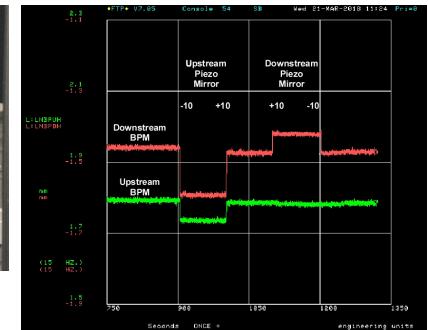
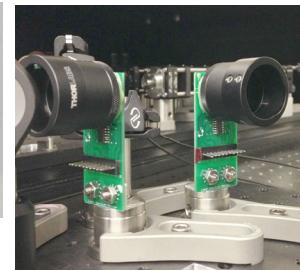
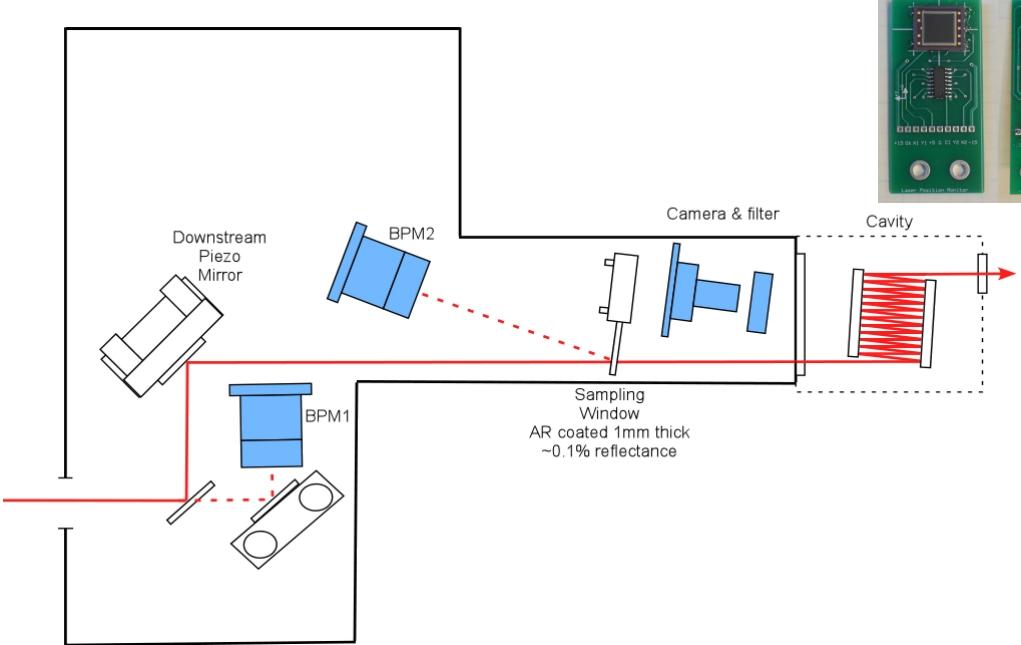
## Laser System: Transport Enclosure

Optical BPM's (developed @FNAL)



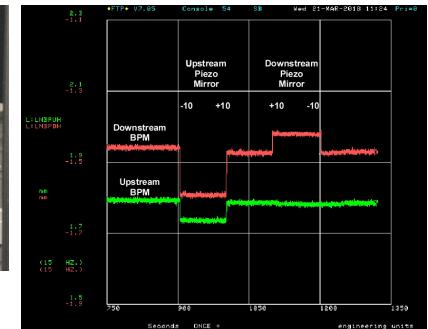
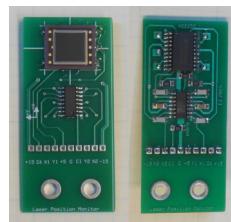
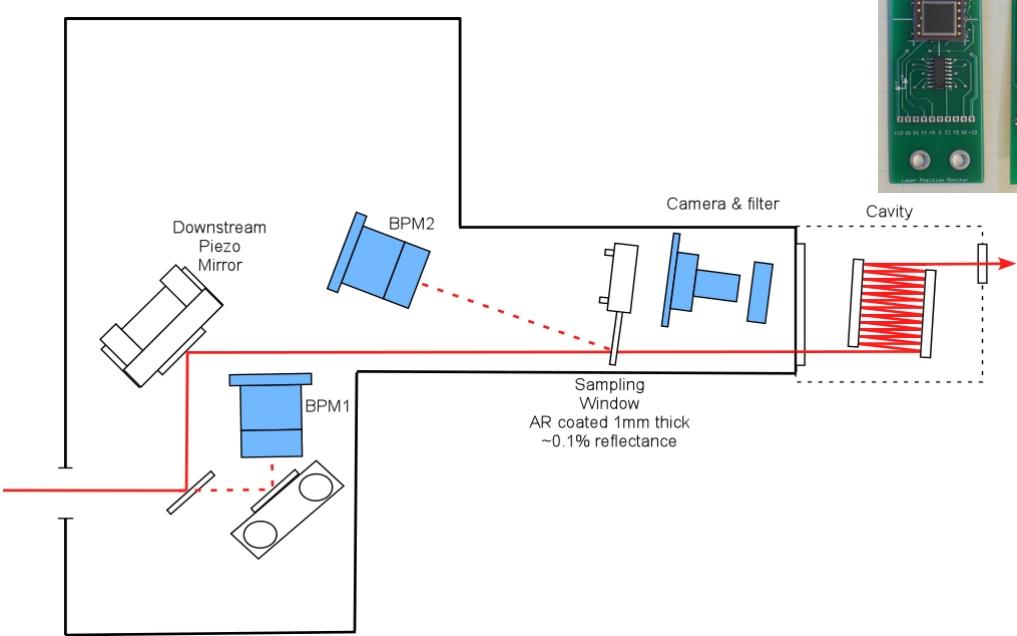
## Laser System: Transport Enclosure

Optical BPM's (developed @FNAL)



## Laser System: Transport Enclosure

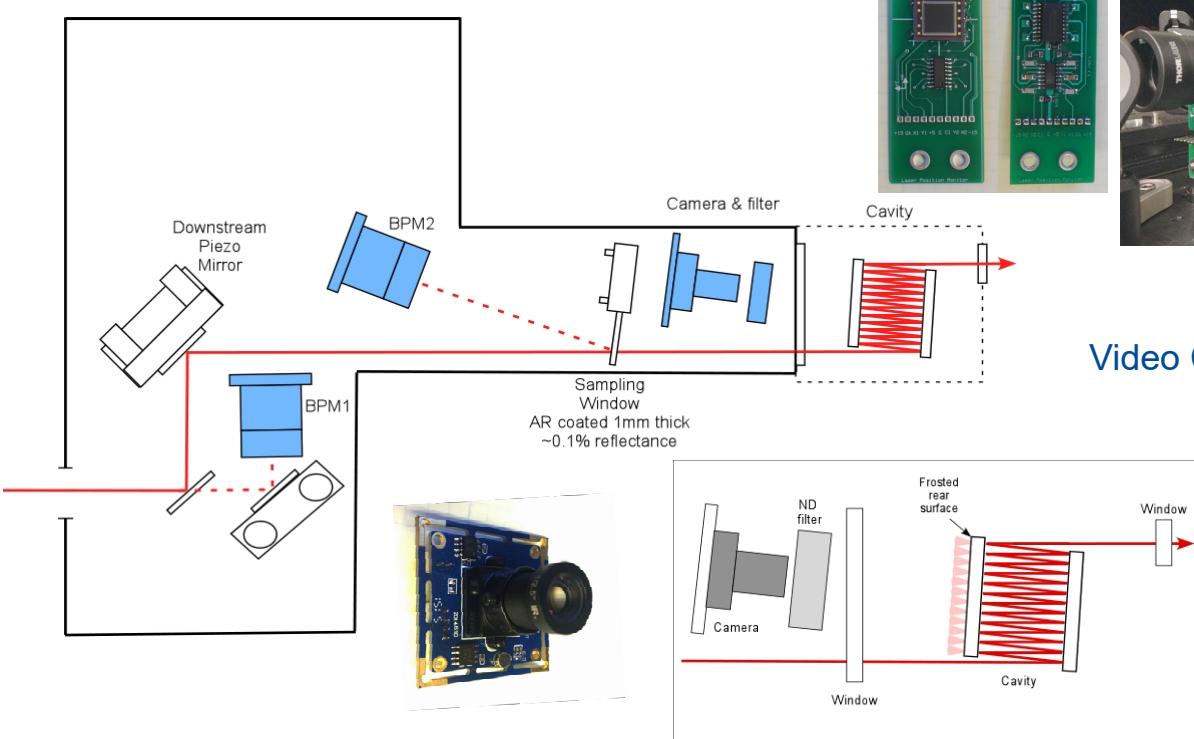
Optical BPM's (developed @FNAL)



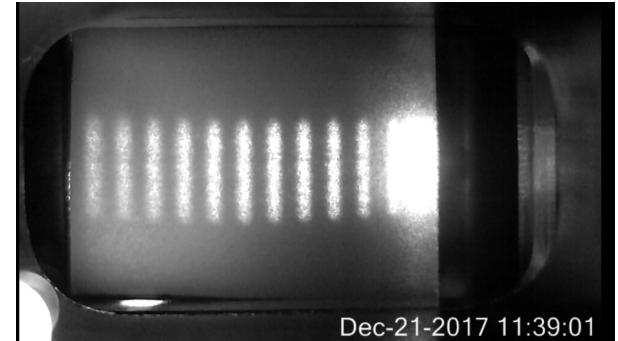
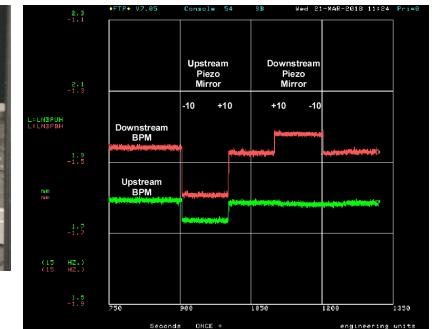
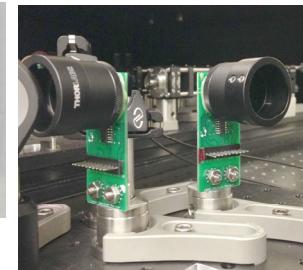
Video Camera

## Laser System: Transport Enclosure

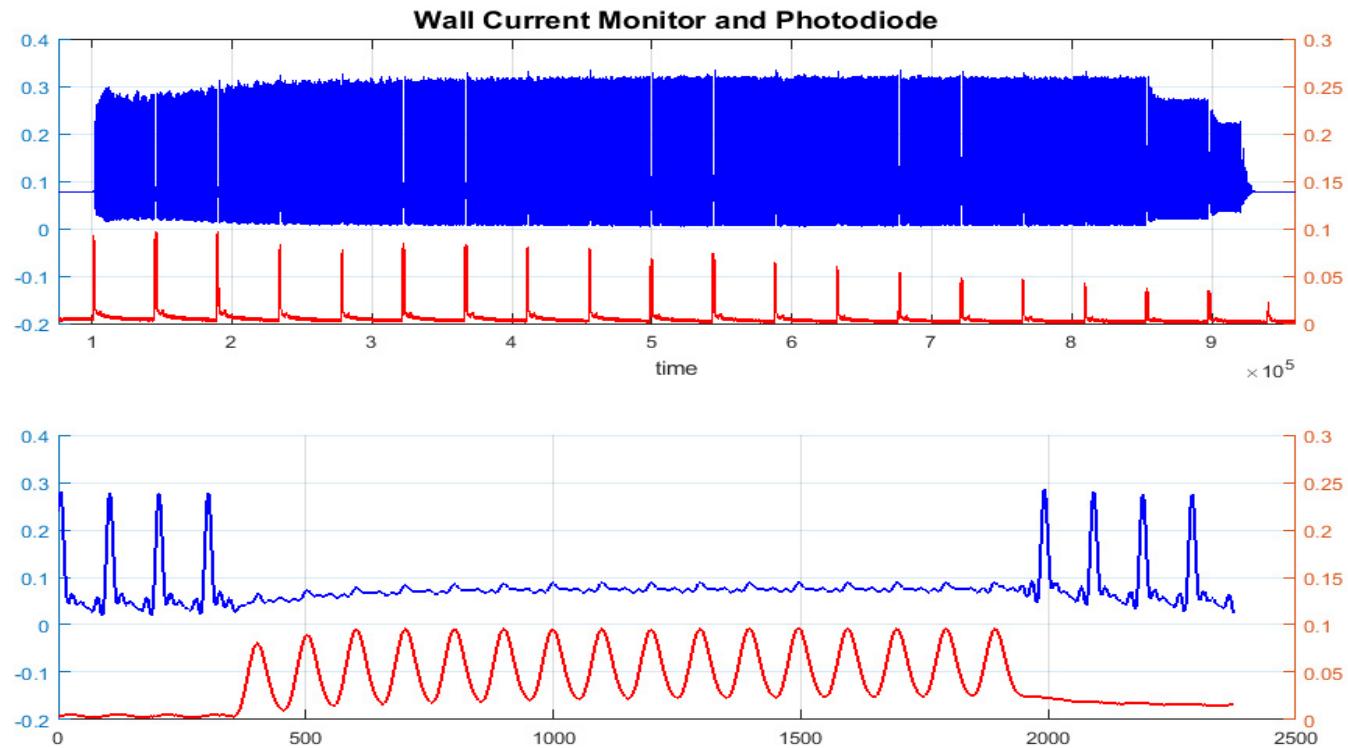
Optical BPM's (developed @FNAL)



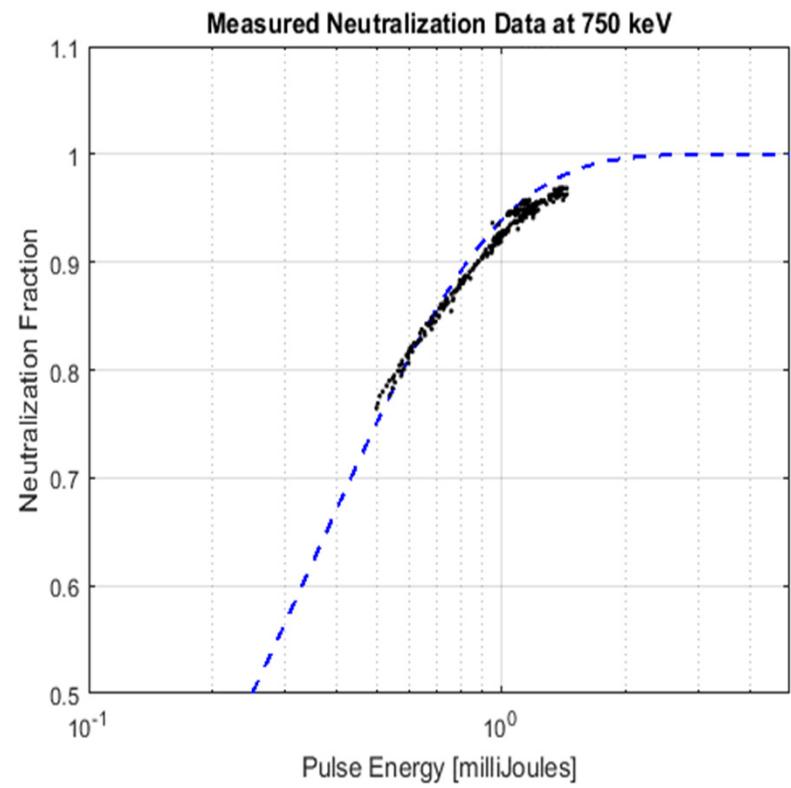
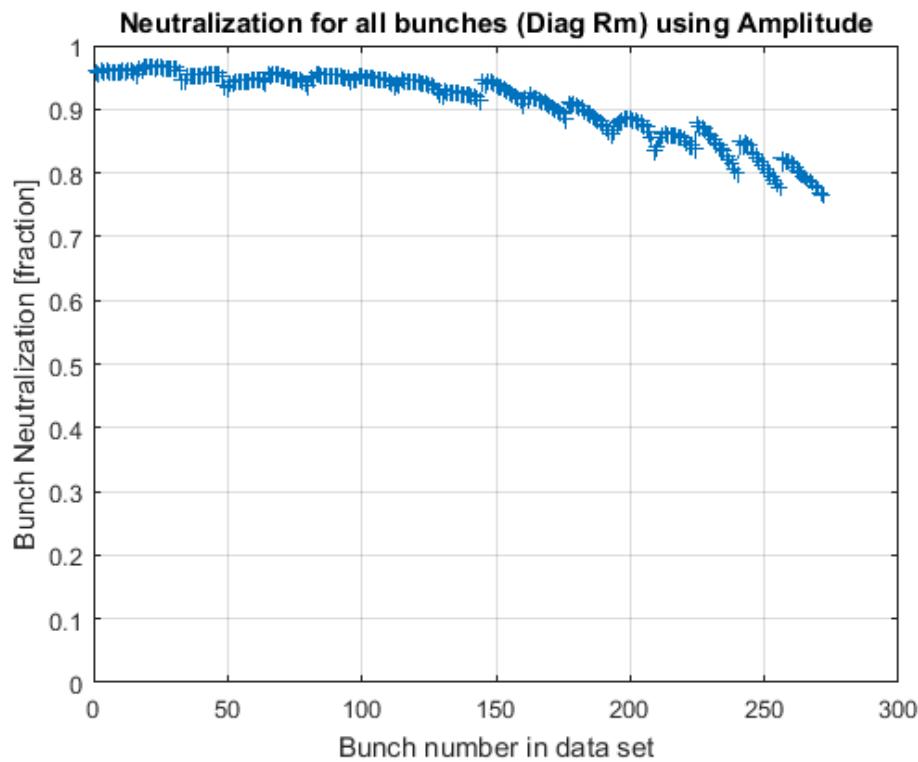
Video Camera



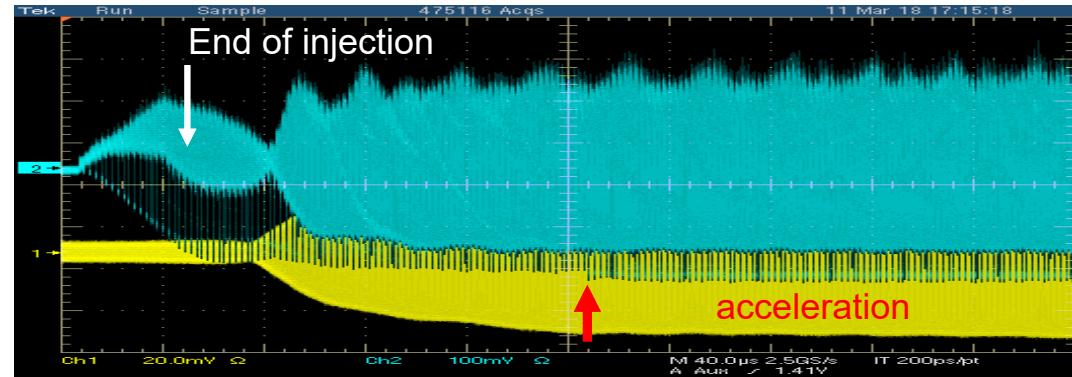
## Laser System: Looking at the Notching Process Linac Signals



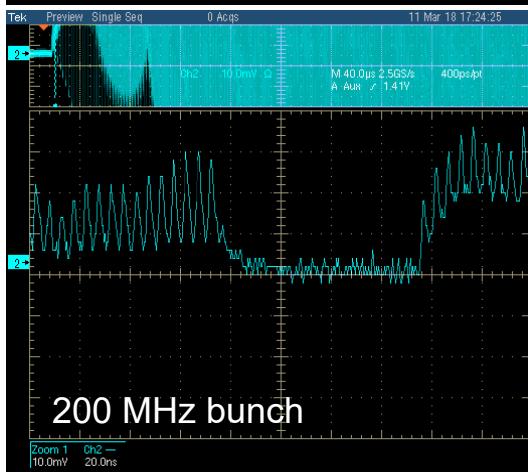
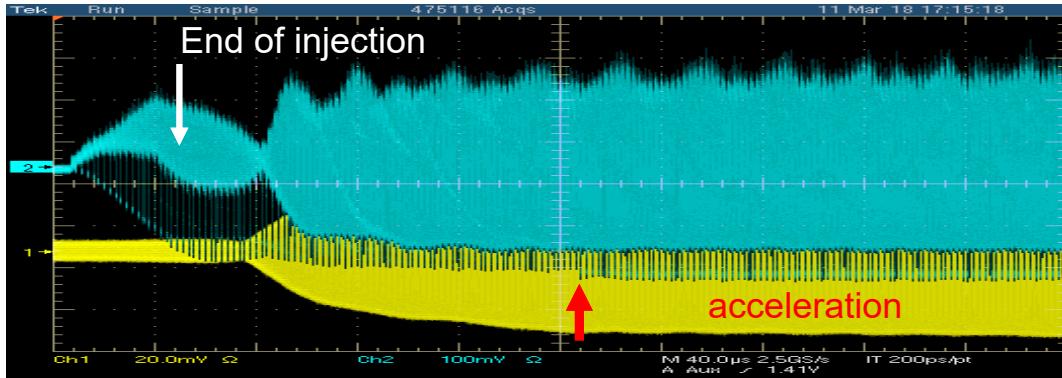
## Laser System: Comparison with Neutralization Estimates



## Notch survival in Booster



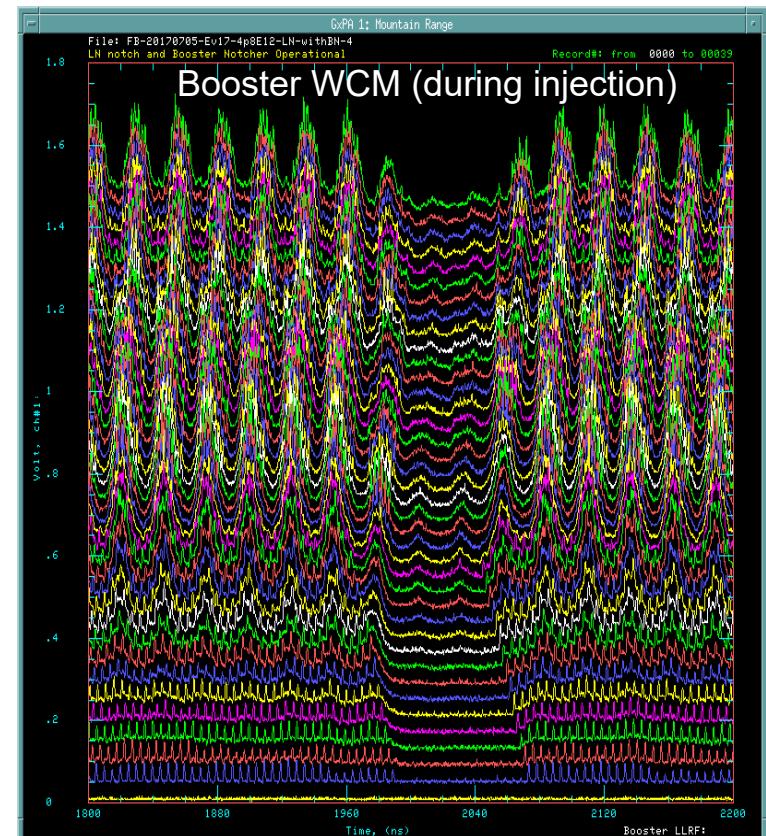
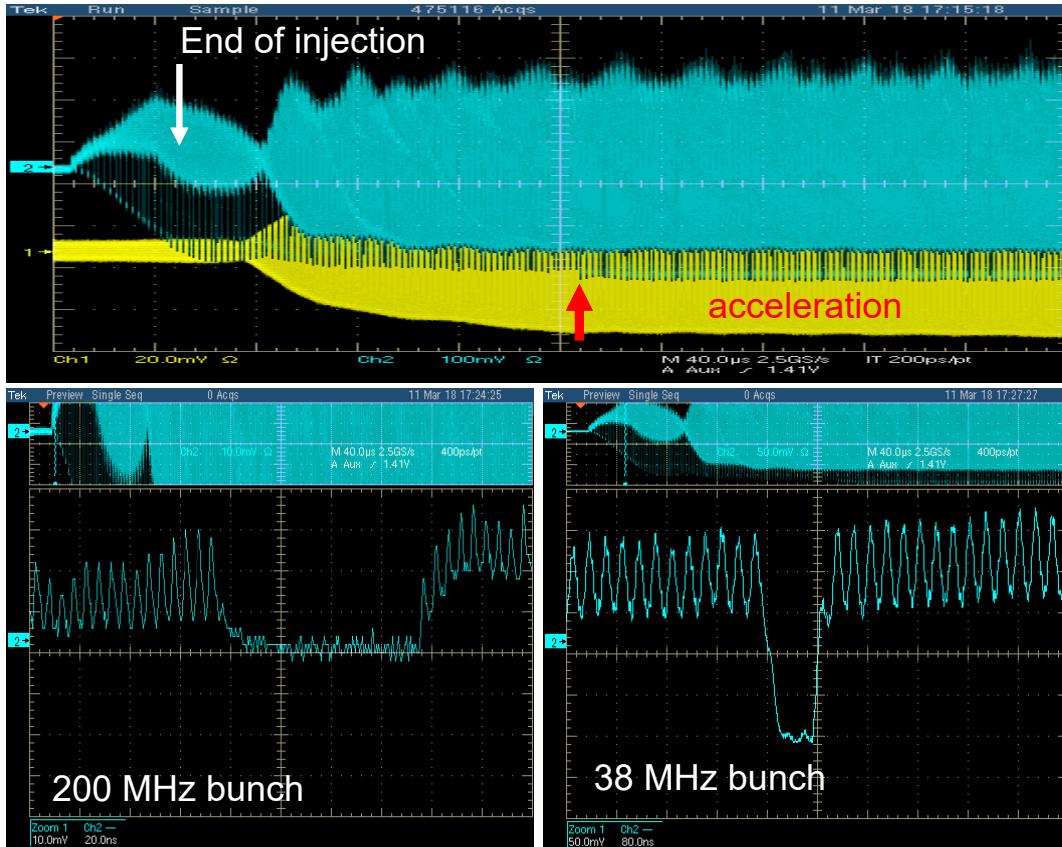
## Notch survival in Booster



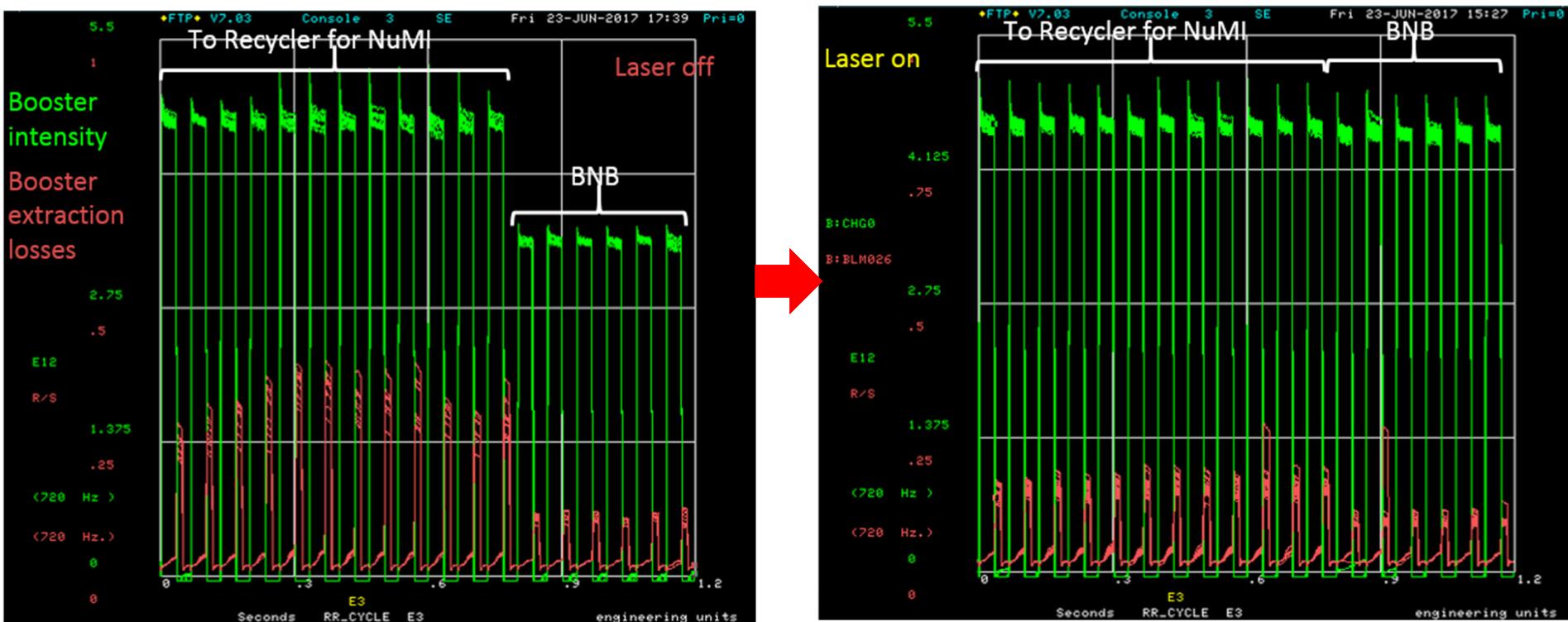
## Notch survival in Booster



## Notch survival in Booster



## Impact of laser Notcher on Booster throughput



## The un-expected

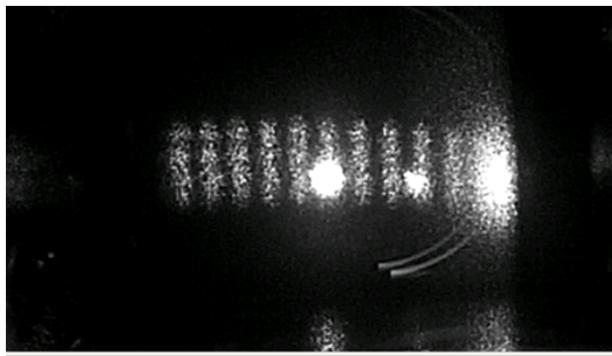
---

- We are seeing damage to the cavity mirrors. Why? Laser pulse intensity well below damage threshold. What's going on? How do we see it real time?

## The un-expected

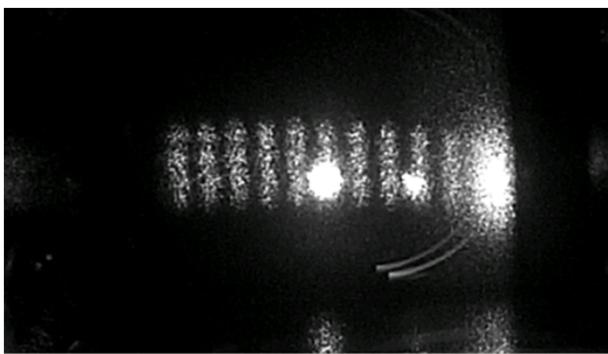
---

- We are seeing damage to the cavity mirrors. Why? Laser pulse intensity well below damage threshold. What's going on? How do we see it real time?



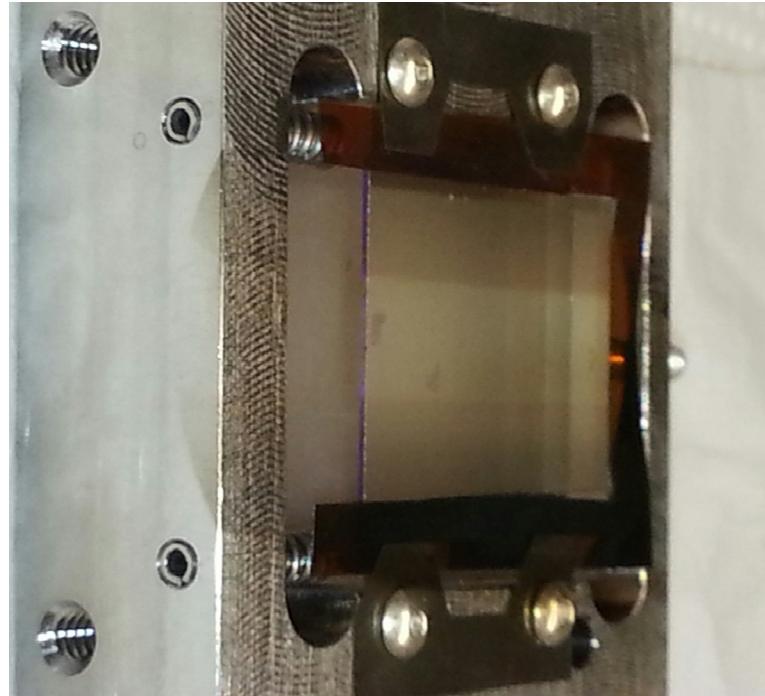
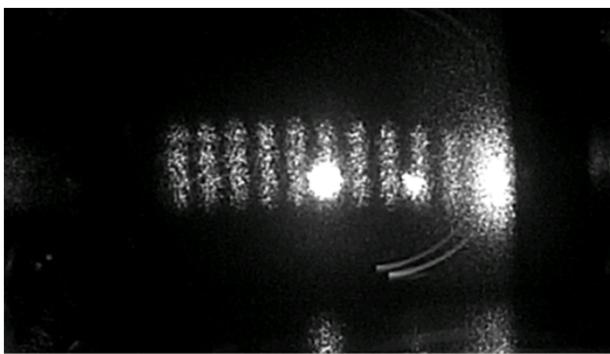
## The un-expected

- We are seeing damage to the cavity mirrors. Why? Laser pulse intensity well below damage threshold. What's going on? How do we see it real time?



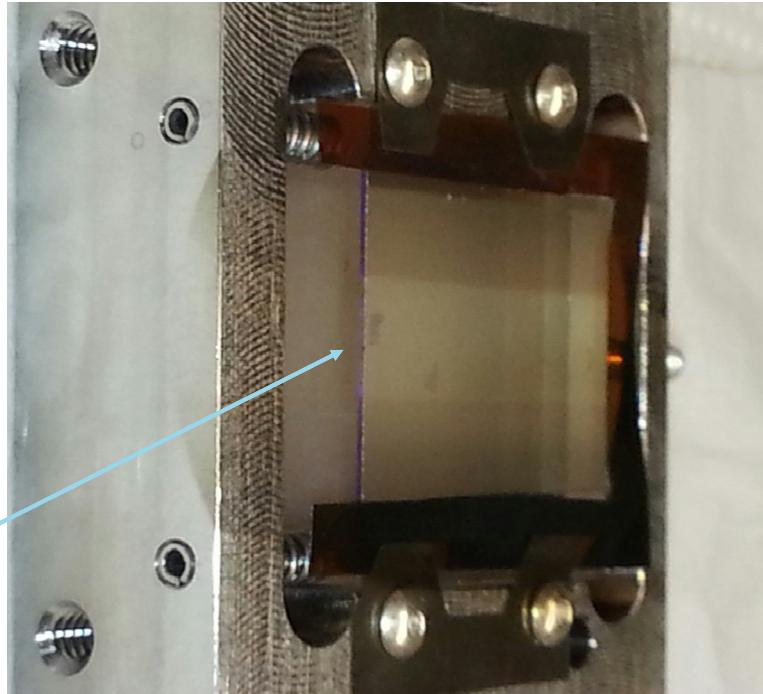
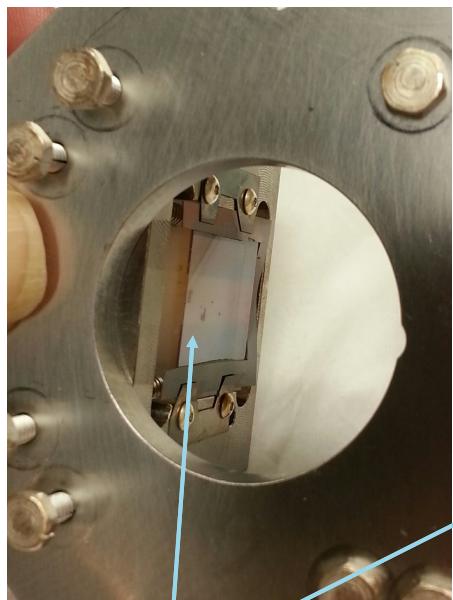
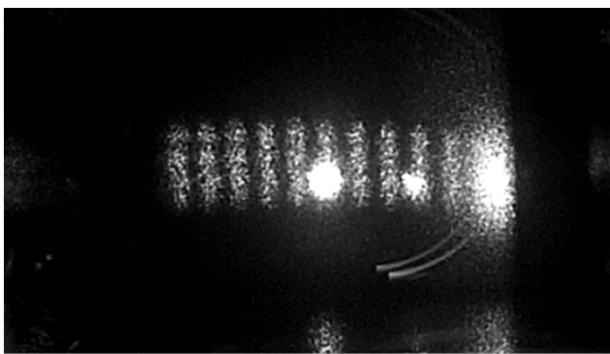
## The un-expected

- We are seeing damage to the cavity mirrors. Why? Laser pulse intensity well below damage threshold. What's going on? How do we see it real time?



## The un-expected

- We are seeing damage to the cavity mirrors. Why? Laser pulse intensity well below damage threshold. What's going on? How do we see it real time?



Let's take a closer look at these damage spots !

## The un-expected

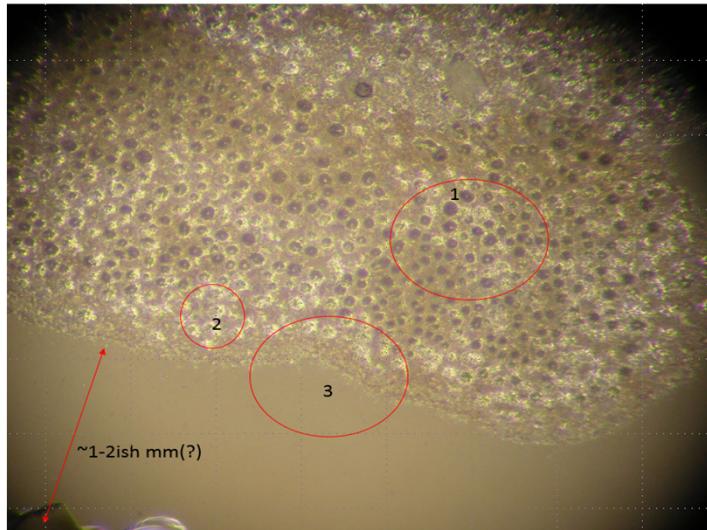
---

>>>Saga on-going <<<



## The un-expected

---

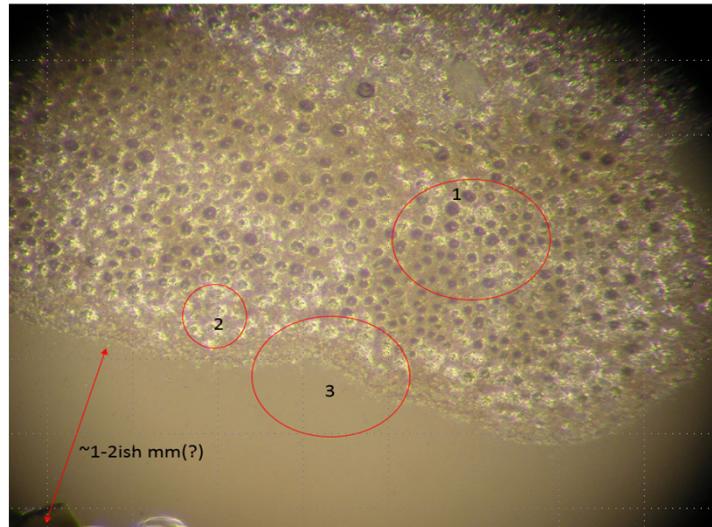


>>>Saga on-going <<<



## The un-expected

---

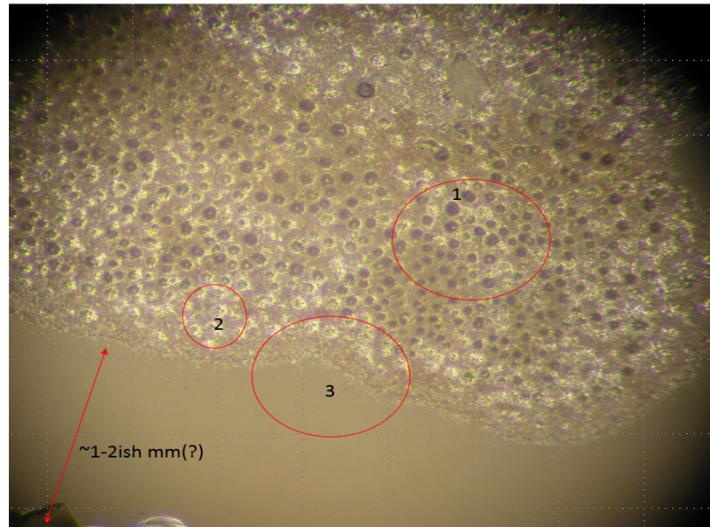


- Preliminary analysis showed Cu being

>>>Saga on-going <<<

## The un-expected

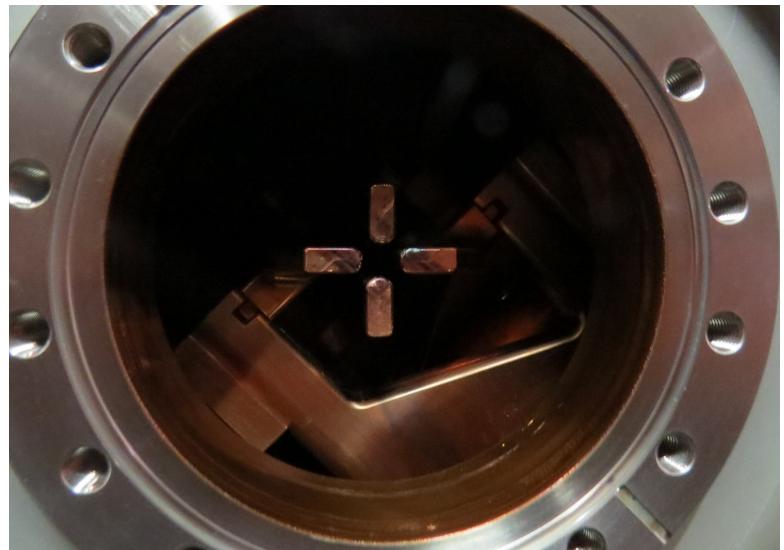
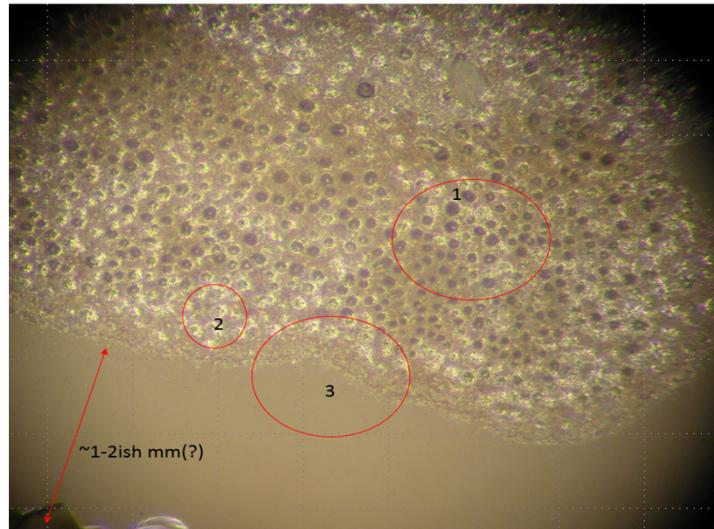
---



- Preliminary analysis showed Cu being deposited on mirror surface ! From WHERE?

>>>Saga on-going <<<

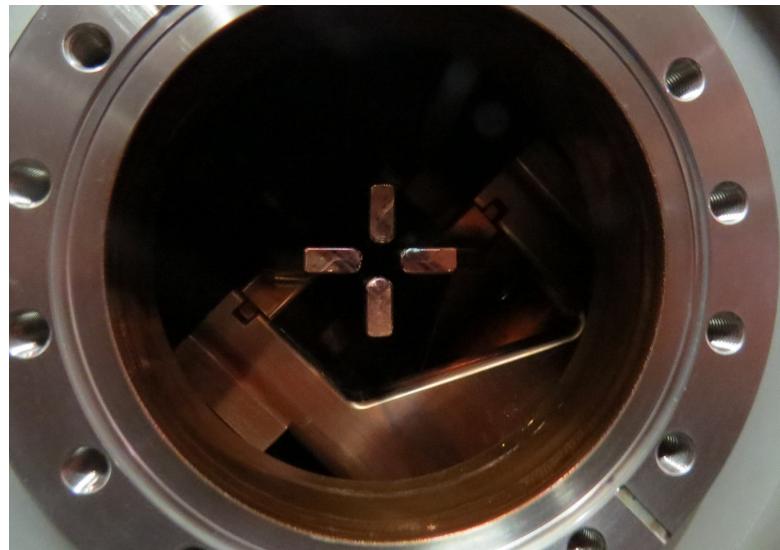
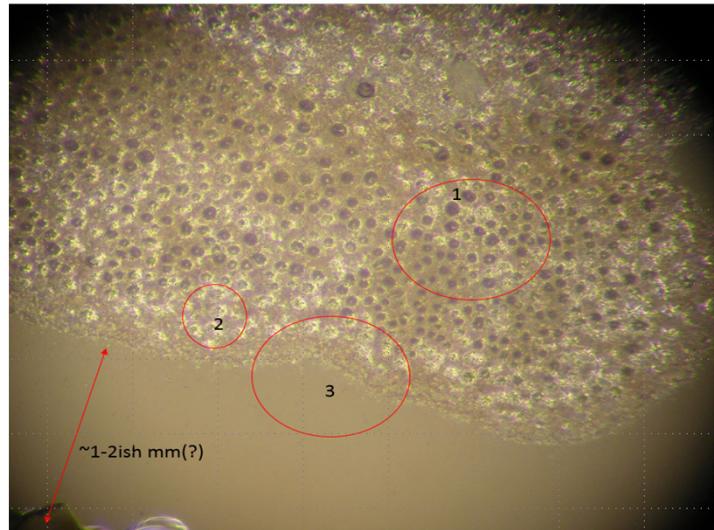
## The un-expected



- Preliminary analysis showed Cu being deposited on mirror surface ! From WHERE?

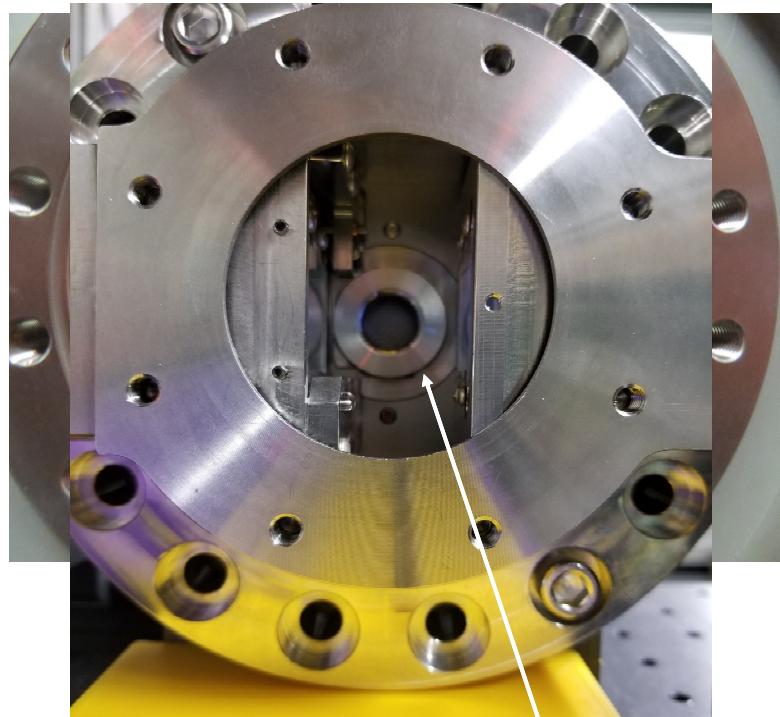
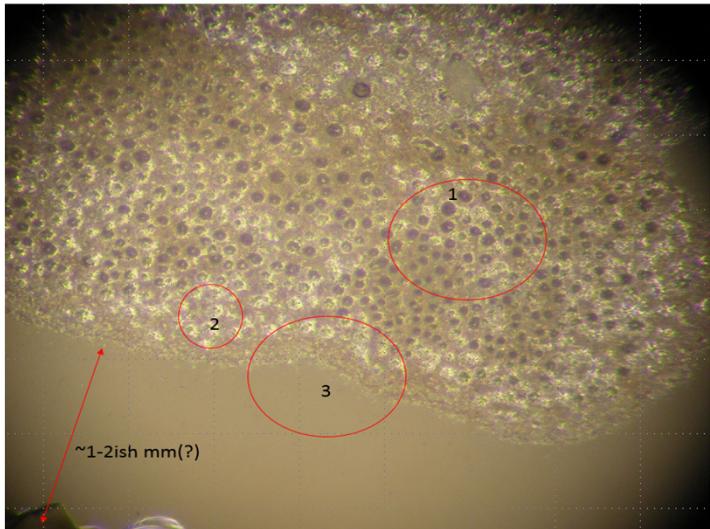
>>>Saga on-going <<<

## The un-expected



- Preliminary analysis showed Cu being deposited on mirror surface ! From WHERE?
- We need to understand how to prevent this from damaging our mirrors !  
**>>>Saga on-going <<<**

## The un-expected



- Preliminary analysis showed Cu being deposited on mirror surface ! From WHERE?
- We need to understand how to prevent this from damaging our mirrors !  
>>>>Saga on-going <<<

First try- a MASK

## Path Forward

---

## Path Forward

---

- The Laser Notcher laser system is a burst-mode, bunch-by-bunch, H- neutralization system that can be tailored for many applications.

## Path Forward

---

- The Laser Notcher laser system is a burst-mode, bunch-by-bunch, H- neutralization system that can be tailored for many applications.
- The final amplifier stage of the laser system was developed specific ion bunch structure which has limitations on average power/duty factor.

## Path Forward

---

- The Laser Notcher laser system is a burst-mode, bunch-by-bunch, H- neutralization system that can be tailored for many applications.
- The final amplifier stage of the laser system was developed specific ion bunch structure which has limitations on average power/duty factor.
- Many of the suggested applications require a system capable of higher duty factor and average power
  - Transverse collimation in one or two planes (in combination with notching)
  - Creation of four beam sections in Booster for the g-2 experiment
  - Longitudinal collimation in a linac where the head and/or tail of a bunch is removed
  - Extinction measurement for the PIP-II mu2e experiment
  - Cleaning the 900 ns no-beam section in the PIP-II mu2e experiment
  - As a potential component for J-PARC laser stripping experiment

## Path Forward

---

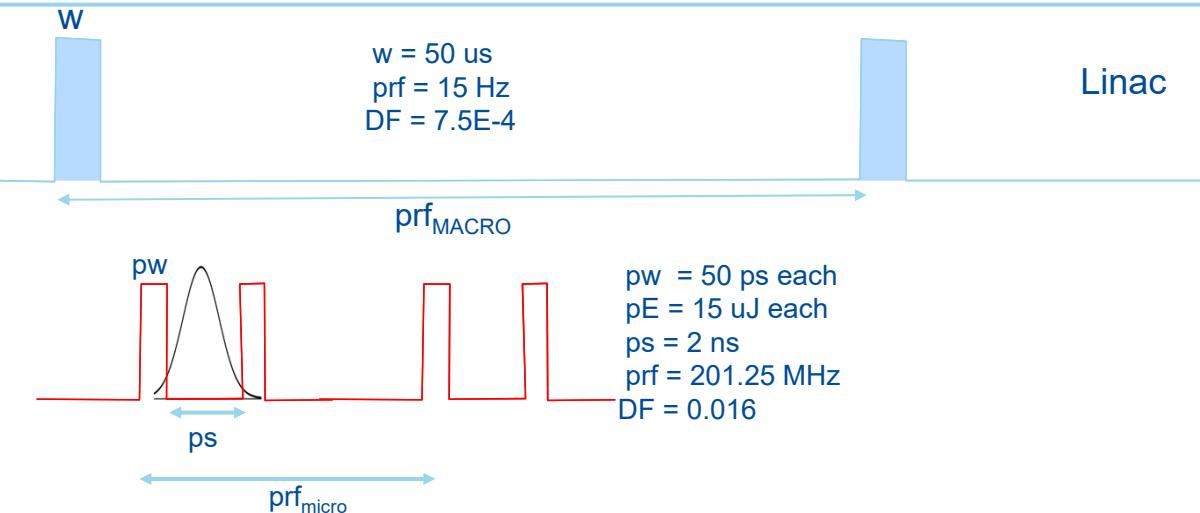
- The Laser Notcher laser system is a burst-mode, bunch-by-bunch, H- neutralization system that can be tailored for many applications.
- The final amplifier stage of the laser system was developed specific ion bunch structure which has limitations on average power/duty factor.
- Many of the suggested applications require a system capable of higher duty factor and average power
  - Transverse collimation in one or two planes (in combination with notching)
  - Creation of four beam sections in Booster for the g-2 experiment
  - Longitudinal collimation in a linac where the head and/or tail of a bunch is removed
  - Extinction measurement for the PIP-II mu2e experiment
  - Cleaning the 900 ns no-beam section in the PIP-II mu2e experiment
  - As a potential component for J-PARC laser stripping experiment
- Each may require a potential different final amplification stage, but can use the infrastructure and technology for the laser notcher.

## Path Forward Continued

---

- We see two areas for further optimizing our amplifier system to be able to support higher duty factor applications
  - Further optimizing optical cavity to reduce required peak laser energy.
  - Move to a fiber only system which is capable of higher duty factors with larger average power and fast pumping
    - The state of art in pulsed fiber amplifiers is 300 kW peak power and 200 W average power.

## Concept for Momentum collimation – shaving longitudinal phase



Split amplified pulse → delay line → recombine temporally with adjustable spacing (ps)  
Create head/tail out of single amplified laser pulse

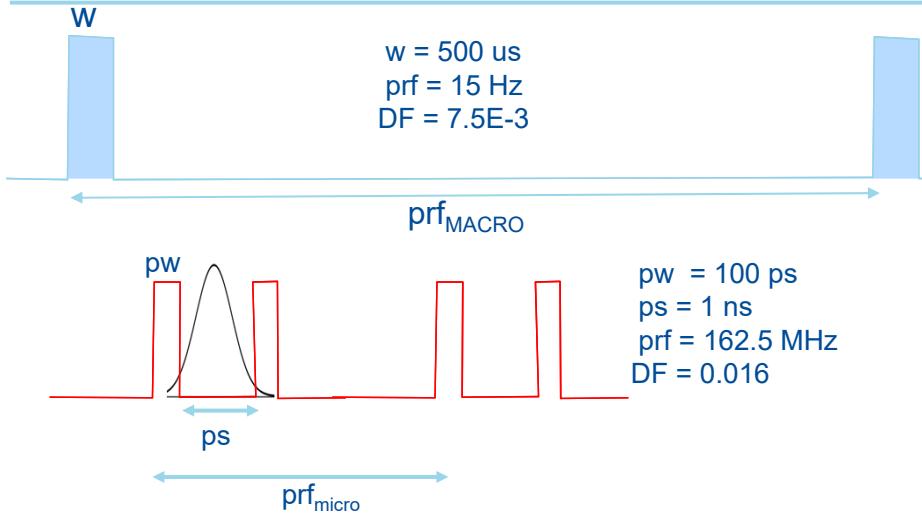
Spot size 1mm x 7.5mm  
50 passes, 0.59 mm separation, 1.19mm at mirror  
cavity length 2.9 cm, laser path 0.73 m,  
neutralization 96% with 15 uJ pulse

Laser produces  $201.25 \times 10^6 \times 50 \times 10^{-6} = 10,000$  pulses /cycle  
For  $30 \mu\text{J}/\text{pulse} \times 10,000 \text{ pulses} = 0.3 \text{ J}/\text{pulse}$

$$\begin{aligned}\text{Peak Power} &= E/\text{pulse}/\text{pulse width} \\ &= 30 \mu\text{J}/0.1 \text{ ns} = 300 \text{ kW}\end{aligned}$$

$$\begin{aligned}\text{Average power} &= \text{Peak power} \times DF \\ &= 300 \text{ kW} \times 3 \times 10^{-5} = 9 \text{ W}\end{aligned}$$

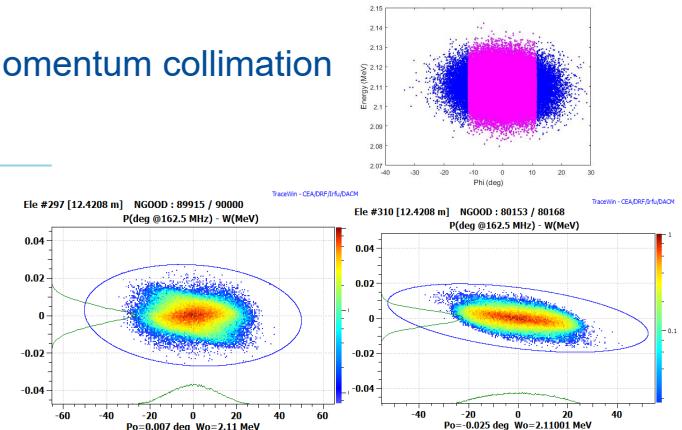
## Path Forward: An Example: Momentum collimation



Split amplified pulse → delay line → recombine temporally with adjustable spacing (ps)  
Create head/tail out of single amplified laser pulse

Spot size 1mm x 1.6mm  
100 passes, 1.1 mm separation, cavity length 10.9 cm  
Laser path 1.6m, neutralization 99.7% with 5 uJ pulse

### PIP-II Momentum collimation



Laser produces  $162.5 \times 10^6 \times 500 \times 10^{-6} = 81,250$  pulses /cycle  
For  $10 \text{ uJ/pulse} \times 81,250 \text{ pulses} = 0.8125 \text{ J/pulse}$

$$\begin{aligned}\text{Peak Power} &= E/\text{pulse}/\text{pulse width} \\ &= 10 \text{ uJ}/0.1 \text{ ns} = 100 \text{ kW}\end{aligned}$$

$$\begin{aligned}\text{Average power} &= \text{Peak power} \times \text{DF} \\ &= 100 \text{ kW} \times 10^{-4} = 10 \text{ W}\end{aligned}$$

## Summary

---

## Summary

---

- We have developed a unique bunch-by-bunch laser system for H- neutralization

## Summary

---

- We have developed a unique bunch-by-bunch laser system for H- neutralization
- System was installed for Operation at the end of January 2018.
  - The Booster losses were ultimately reduced ~30% and the beam throughput to the Experiments (particularly BNB) was increased by ~30%
  - Improvements continue to be made to the complete system as we gain operational experience.

## Summary

---

- We have developed a unique bunch-by-bunch laser system for H- neutralization
- System was installed for Operation at the end of January 2018.
  - The Booster losses were ultimately reduced ~30% and the beam throughput to the Experiments (particularly BNB) was increased by ~30%
  - Improvements continue to be made to the complete system as we gain operational experience.
- This flexibility can be applied to many applications, not only in H- manipulation, but in any application requiring multi-MHz pulses in a continuous or burst mode

## Summary

---

- We have developed a unique bunch-by-bunch laser system for H- neutralization
- System was installed for Operation at the end of January 2018.
  - The Booster losses were ultimately reduced ~30% and the beam throughput to the Experiments (particularly BNB) was increased by ~30%
  - Improvements continue to be made to the complete system as we gain operational experience.
- This flexibility can be applied to many applications, not only in H- manipulation, but in any application requiring multi-MHz pulses in a continuous or burst mode
- Fermilab continues to develop technology in non-resonant interaction cavities.

## Summary

---

- We have developed a unique bunch-by-bunch laser system for H- neutralization
- System was installed for Operation at the end of January 2018.
  - The Booster losses were ultimately reduced ~30% and the beam throughput to the Experiments (particularly BNB) was increased by ~30%
  - Improvements continue to be made to the complete system as we gain operational experience.
- This flexibility can be applied to many applications, not only in H- manipulation, but in any application requiring multi-MHz pulses in a continuous or burst mode
- Fermilab continues to develop technology in non-resonant interaction cavities.
- Fermilab will continue to develop laser system with a high peak, high average power quasi-CW laser systems suitable for full linac pulse neutralization applications.

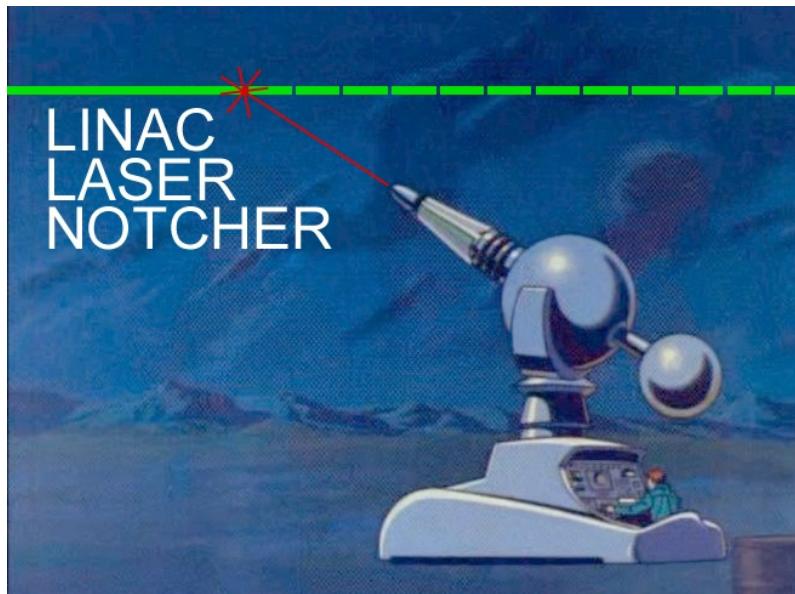
## Summary

---

- We have developed a unique bunch-by-bunch laser system for H- neutralization
- System was installed for Operation at the end of January 2018.
  - The Booster losses were ultimately reduced ~30% and the beam throughput to the Experiments (particularly BNB) was increased by ~30%
  - Improvements continue to be made to the complete system as we gain operational experience.
- This flexibility can be applied to many applications, not only in H- manipulation, but in any application requiring multi-MHz pulses in a continuous or burst mode
- Fermilab continues to develop technology in non-resonant interaction cavities.
- Fermilab will continue to develop laser system with a high peak, high average power quasi-CW laser systems suitable for full linac pulse neutralization applications.
- We see this approach as contributing to the further growth in the utilizing of laser interactions with H- for a variety of applications.

---

# Thank you for your attention



## Questions ?